

*Lecture 1:*

# Intro to MEMS

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# What is MEMS ?

- Different physics in nano and micro scales
  - High viscosity ( $>$  inertia), stiction, friction & surface tension are dominant in micro world



From *Scientific American*, November 1992



Antz, Dreamworks



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# What is MEMS ?

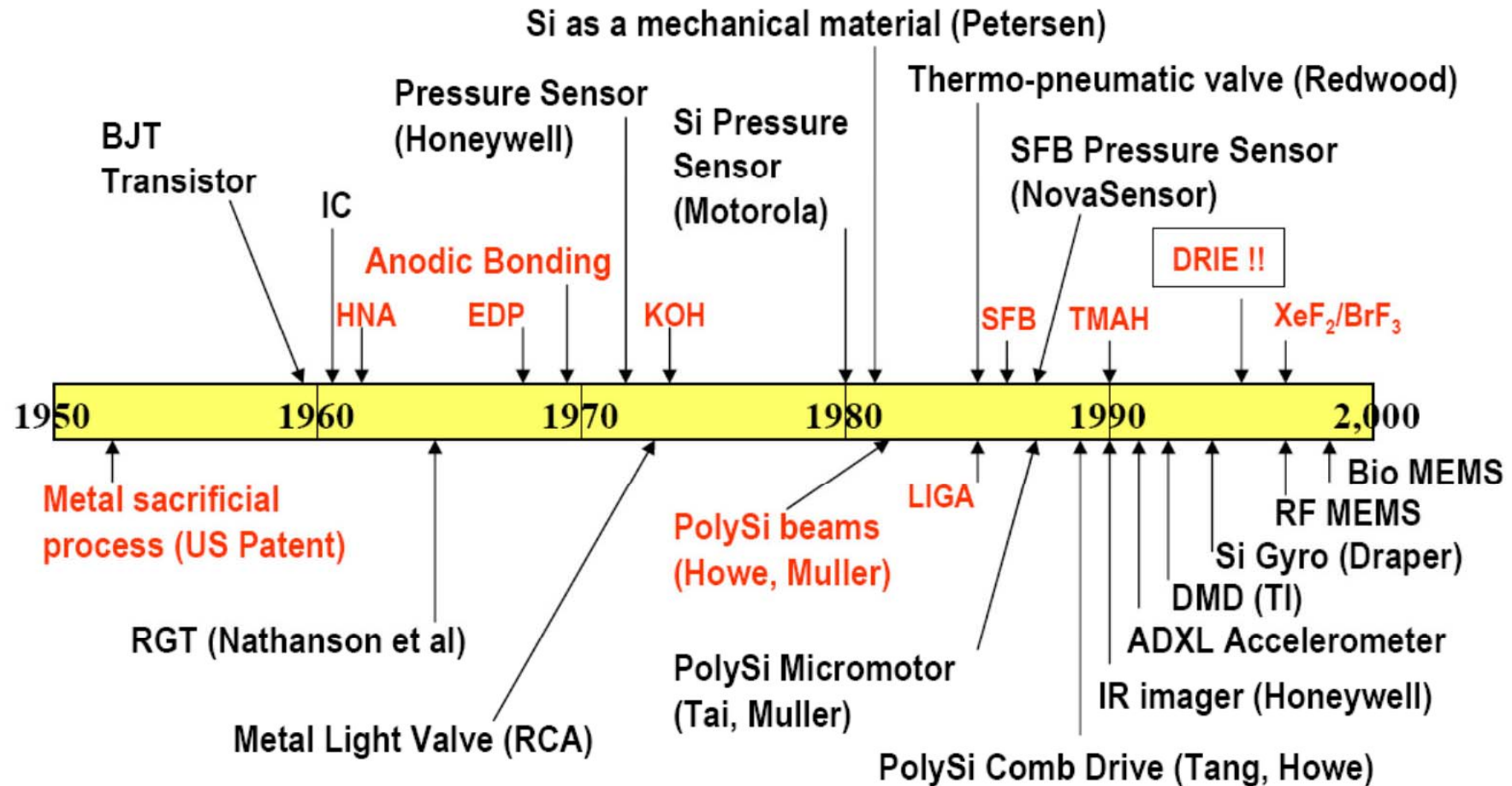
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- **MicroElectroMechanical Systems**
- The fabrication of devices with at least some of their dimensions in the micrometer range.
- Increase performance and decrease cost.
- Application for *electronics, communications, mechatronics, medicine, military*
- Commercial product : *an accelerometer sensor for the car air-bag, an inkjet printer header, a pressure sensor, components of RF and Optics*
- As a new solution for IT, BT, ET, and NT many countries investment MEMS.



# What is MEMS ?

- A brief MEMS history



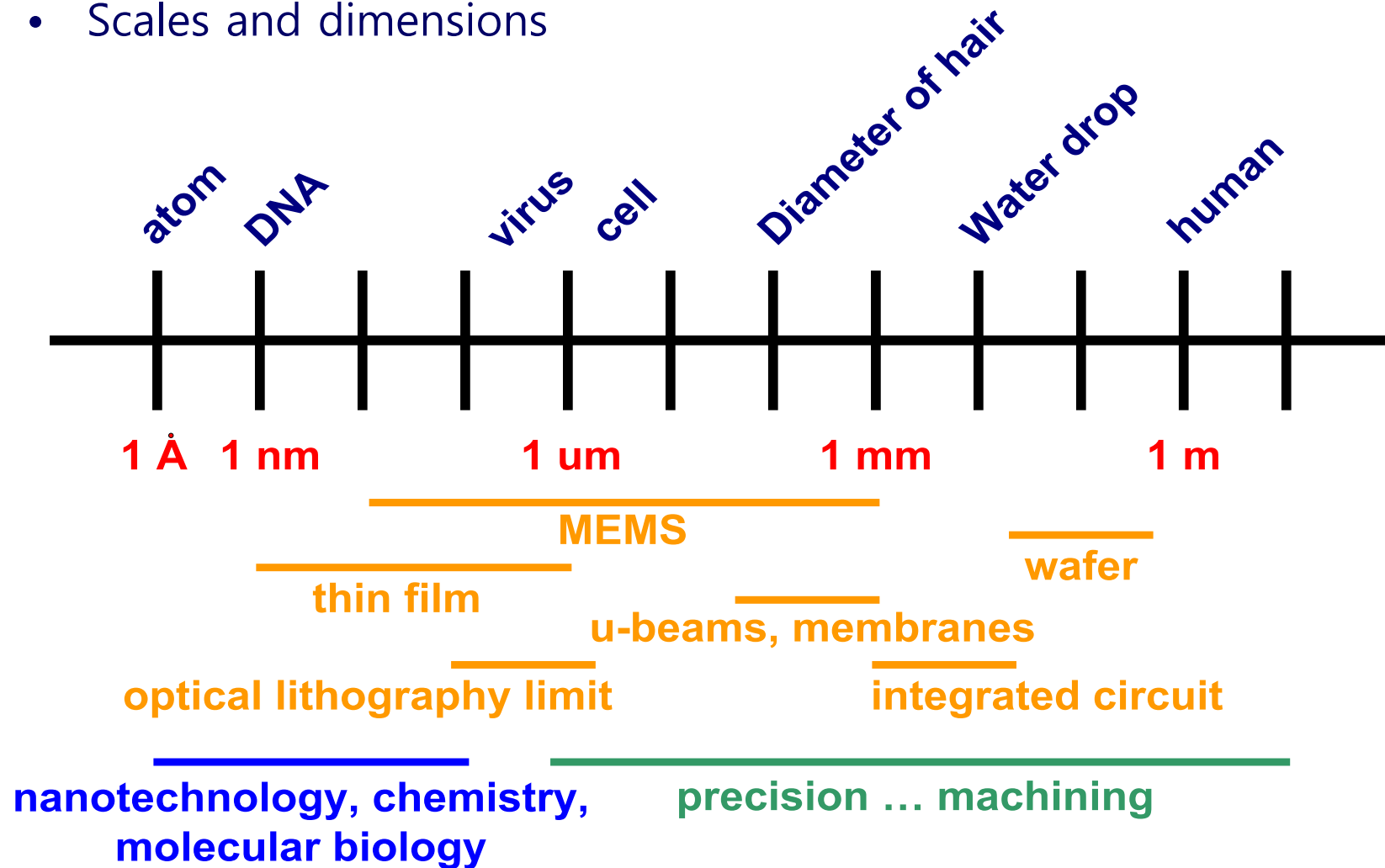
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# What is MEMS ?

- Scales and dimensions



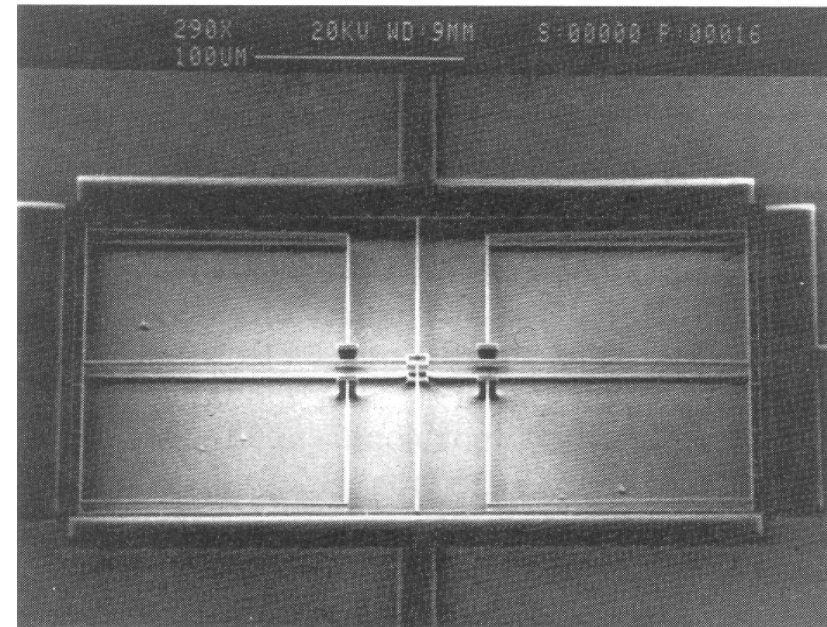
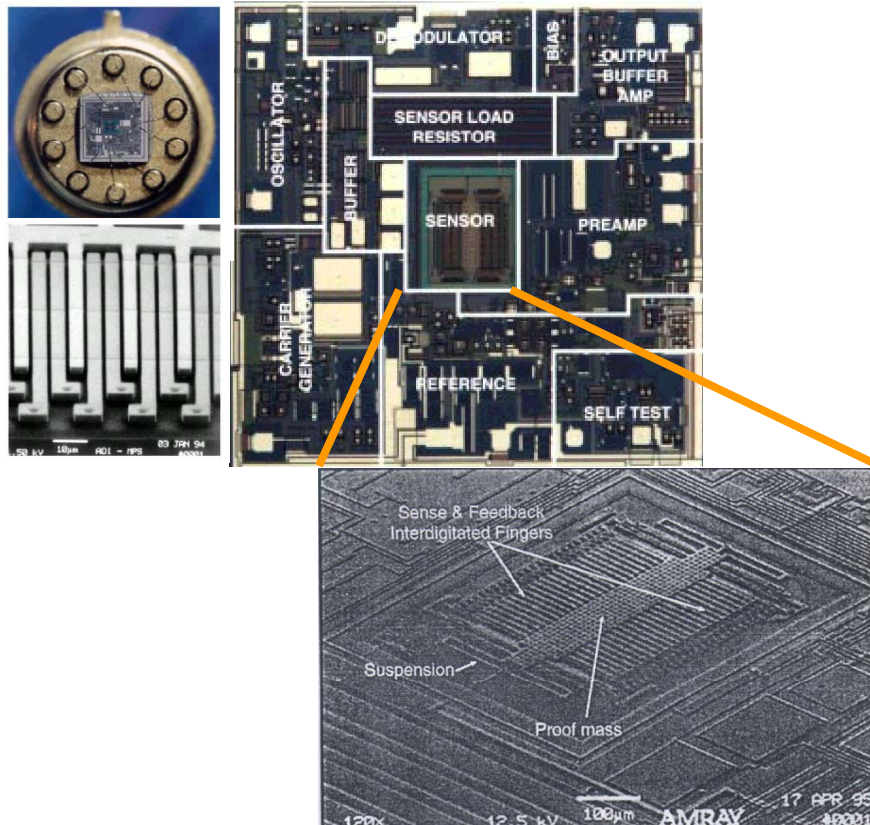
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# What is MEMS ?

- Uses IC manufacturing techniques to fabricate moving structures in micro scale



(Cornell)

([Http://www.analog.com](http://www.analog.com))



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# What is MEMS ?

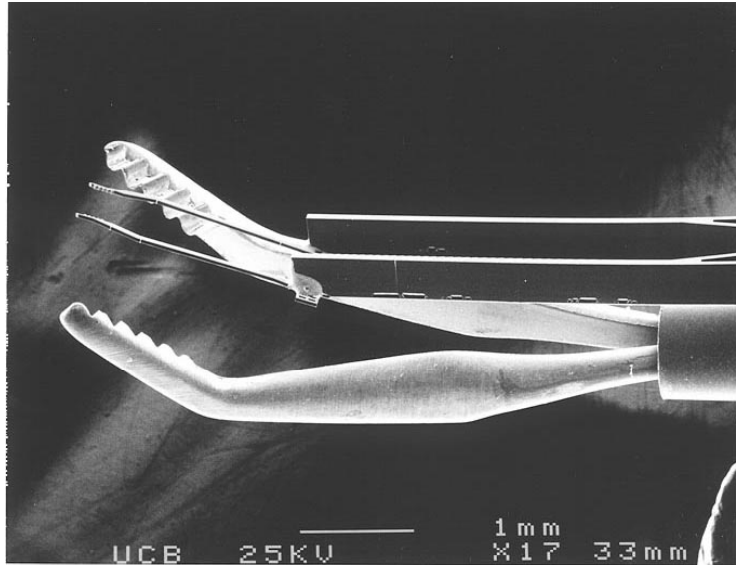
- Scaling law
  - As system becomes smaller, the scaling of the force also determines the acceleration,  $a$ ; transit time,  $t$ ; power per unit volume  $P/V_0$  generated and dissipated
  - the mass of a system :  $m$ , scales as  $(S^3)$
  - for generalized case with a force  $F$  scaling as  $(S^F)$
  - where  $x$  = distance

$$\begin{array}{l}
 F = \begin{bmatrix} S^1 \\ S^2 \\ S^3 \\ S^4 \end{bmatrix} \\
 a = \frac{F}{m} = [S^F][S^{-3}] \\
 t = \sqrt{\frac{2xm}{F}} = ([S^1][S^3][S^{-F}])^{\frac{1}{2}} \\
 \frac{P}{V_0} = \frac{Fx}{tV_0}
 \end{array}
 \quad
 \begin{array}{l}
 F = \begin{bmatrix} S^1 \\ S^2 \\ S^3 \\ S^4 \end{bmatrix} \Rightarrow a = \begin{bmatrix} S^{-2} \\ S^{-1} \\ S^0 \\ S^1 \end{bmatrix} \Rightarrow t = \begin{bmatrix} S^{1.5} \\ S^1 \\ S^{0.5} \\ S^{2.0} \end{bmatrix} \\
 \frac{P}{V_0} = \begin{bmatrix} S^{-2.5} \\ S^{-1} \\ S^{0.5} \\ S^2 \end{bmatrix}
 \end{array}$$

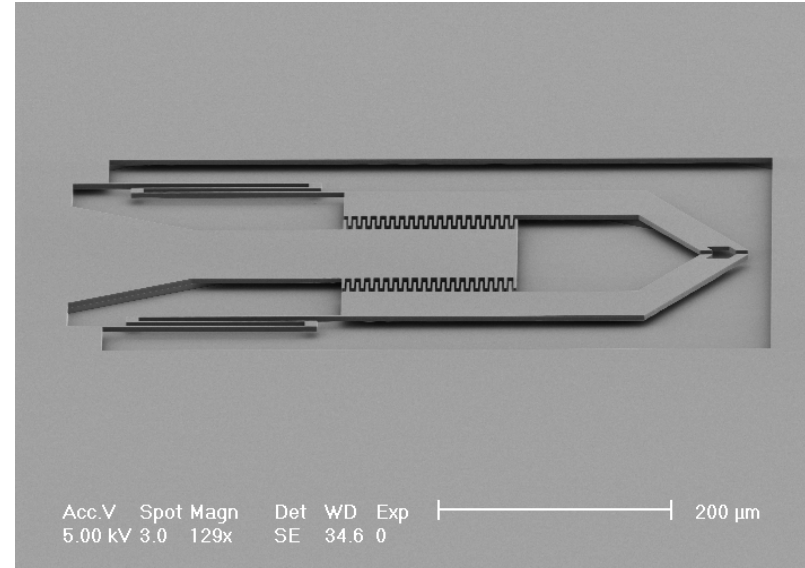


# What is MEMS ?

- Long slender beams are very strong in micro scale



[Http://www.memspi.com](http://www.memspi.com)



Nano/Micro Systems & Controls Lab, SNU

- But moving through air in micro scale is difficult (like swimming in molasses)



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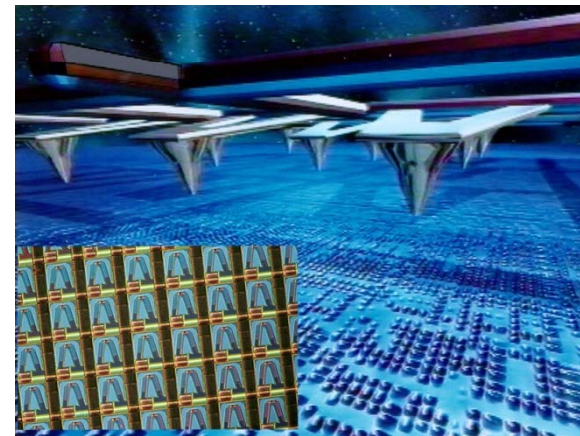


# What are MEMS driving forces ?

- **M**iniaturization
  - Small feature: fast, precise, gentle, reach narrow space
- **M**ultiplicity
  - Batch fabrication: mass production, low cost
  - Pre-assembled system and parallel processing: high density
- **M**icroelectronics
  - Integration with electronic circuits



Wearable PC



IBM Millipede  
(800 Gbit/in<sup>2</sup>)

HDD: 230 Gbit/in<sup>2</sup>  
DRAM: 10 Gbit/in<sup>2</sup>  
Fresh RAM: 250 Mbit/in<sup>2</sup>



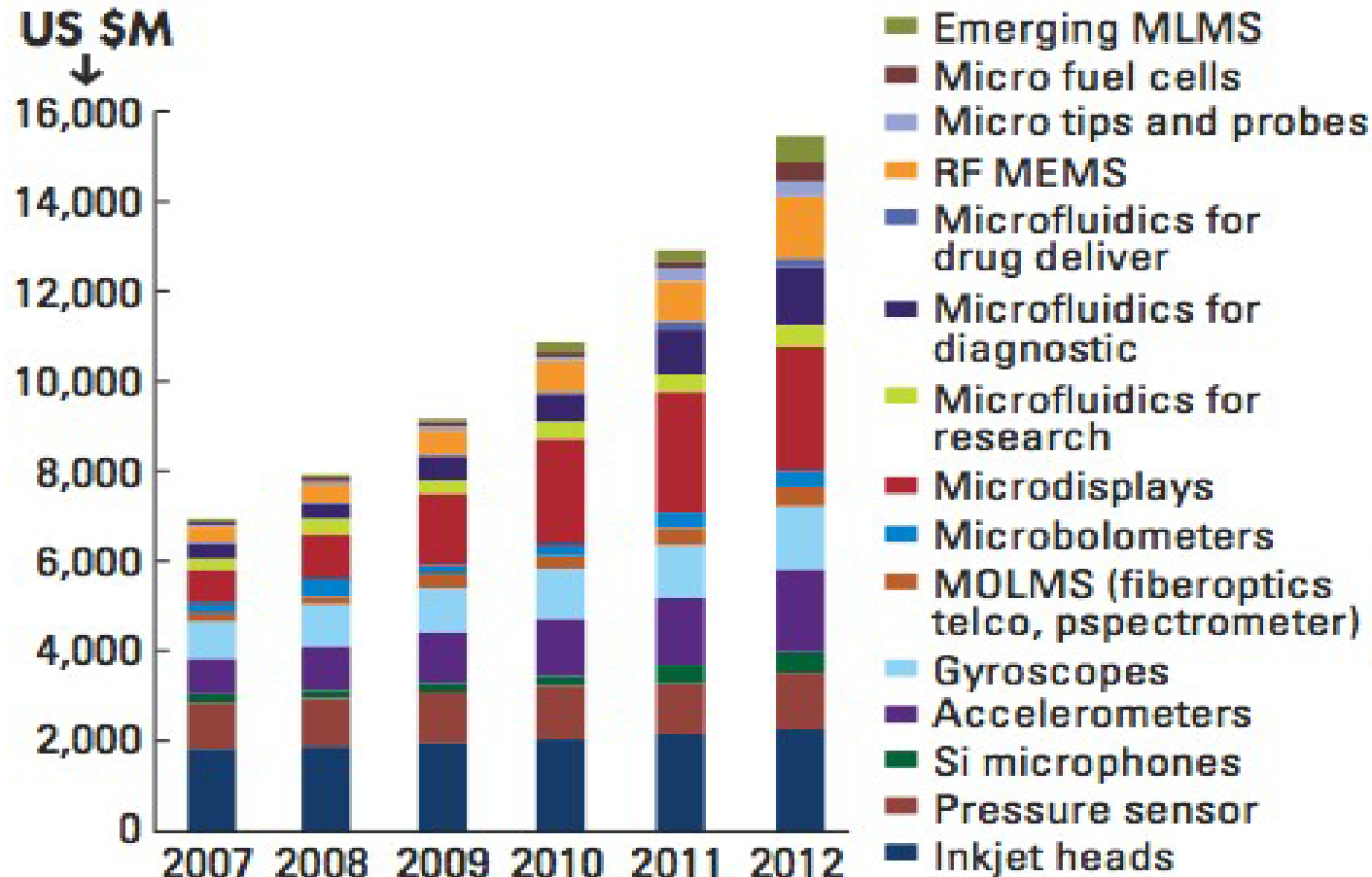
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# MEMS Market

## MEMS Market Forecast, 2007-2012



Source: Yole Développement, July 2008

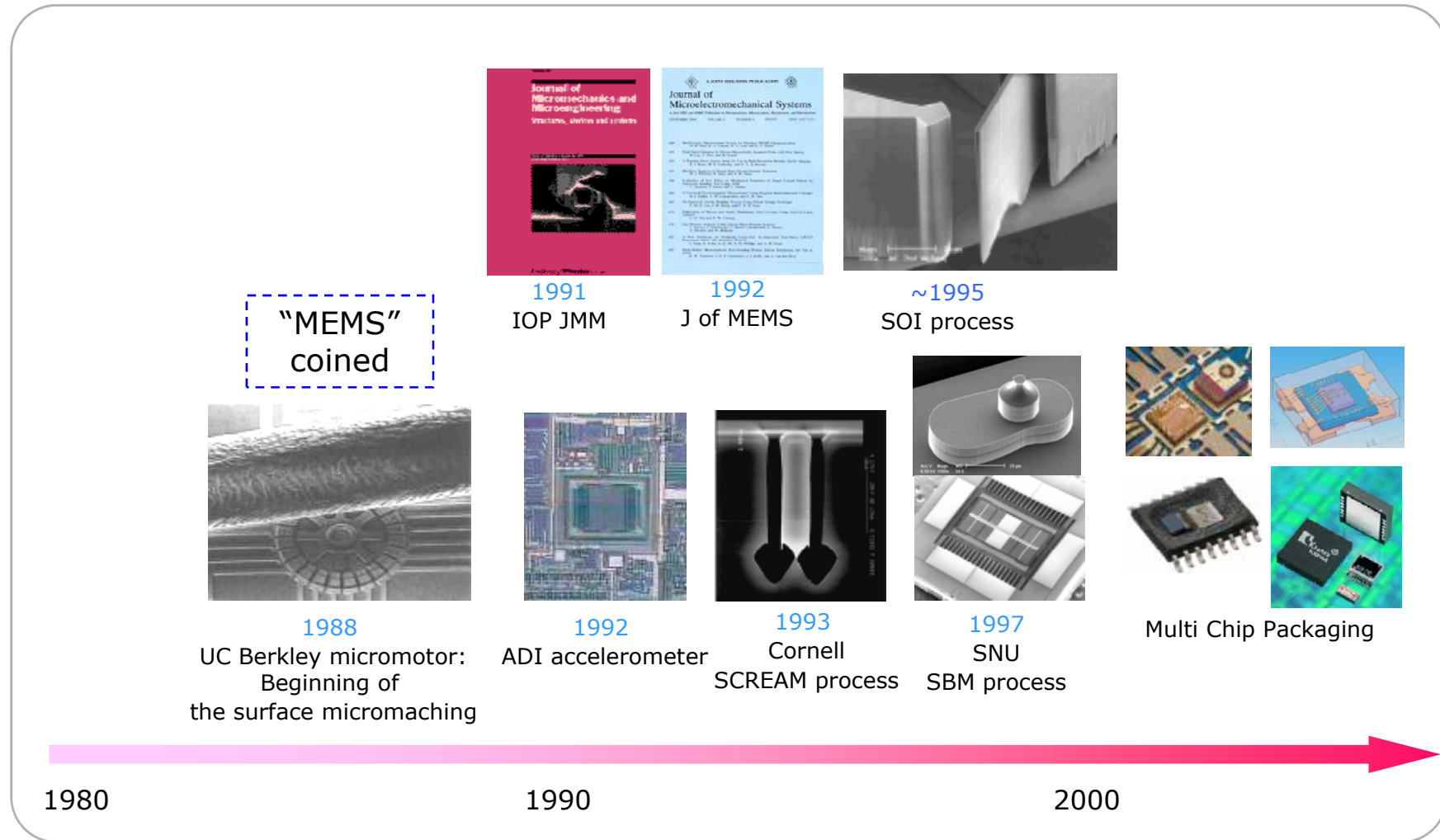


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# Intro to Micromachining



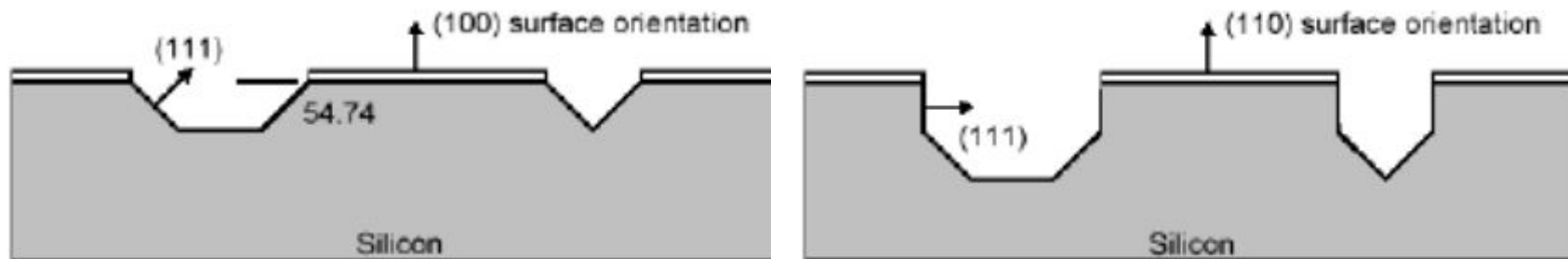
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# Bulk Micromachining (70's)

- Anisotropic wet etching
  - Anisotropic etchants etch much faster in one direction than in another
    - Exposing the slowest etching crystal planes over time
    - (111) planes have the slowest etch rate
  - Several solutions: Alkalic OH (KOH, NaOH), TMAH, EDP
  - Etching at concave corners on (100), stop at (111) intersections, convex corners are under cut



Silicon anisotropic wet etching of (100) and (110) silicon



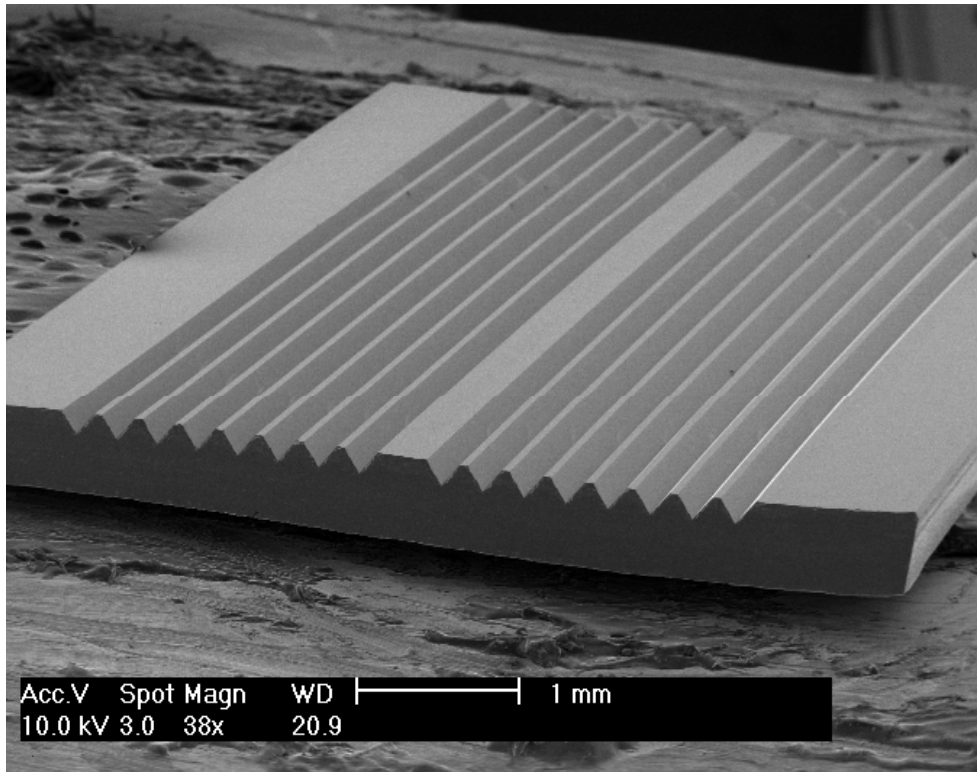
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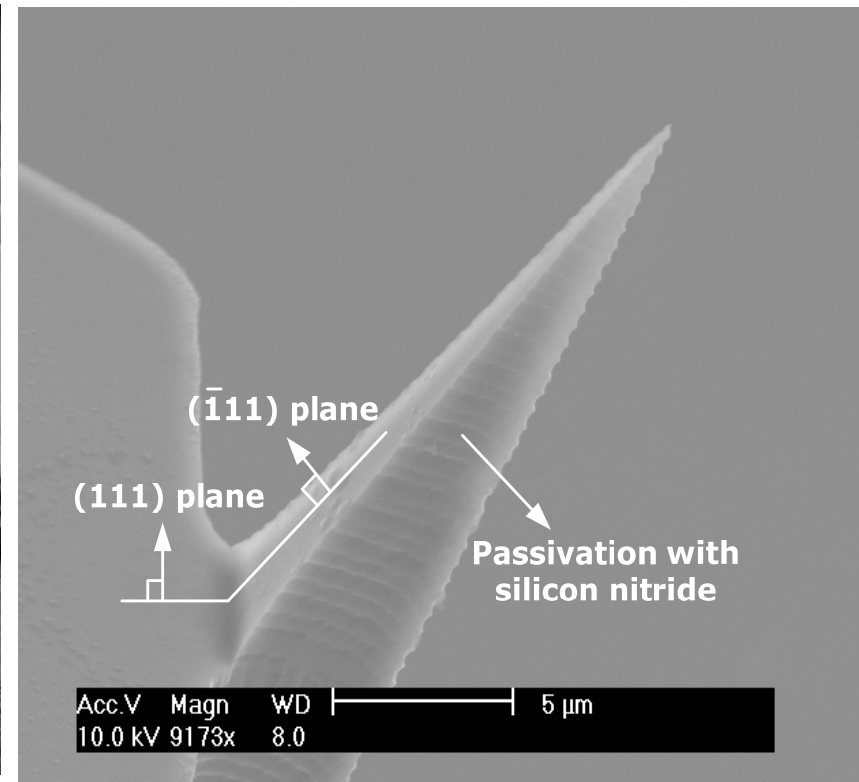
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# Bulk Micromachining (70's)

- Anisotropic silicon etching



Optical bench using (100) silicon



Silicon tip using (111) silicon

(SNU NML)



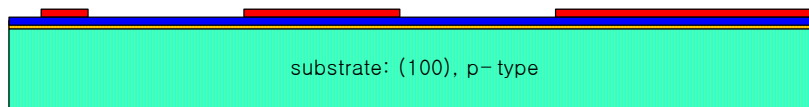
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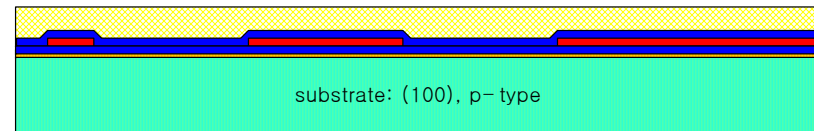
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# Surface Micromachining ('85-'95)

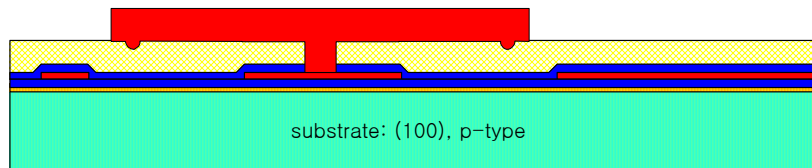
- Typical surface micromachining process steps
  - In HF, oxide etches fast for sacrificial release



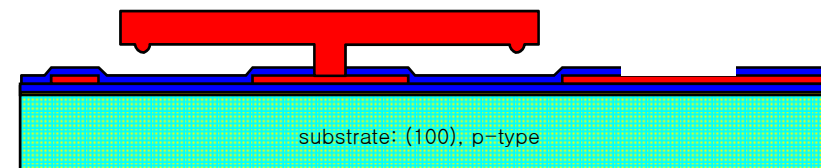
(a) oxide/nitride deposition, polysilicon deposition & patterning



(b) nitride deposition, sacrificial oxide deposition



(c) anchor patterning, polysilicon deposition & patterning



(d) sacrificial wet etch in HF

(SNU MEMS MPC)



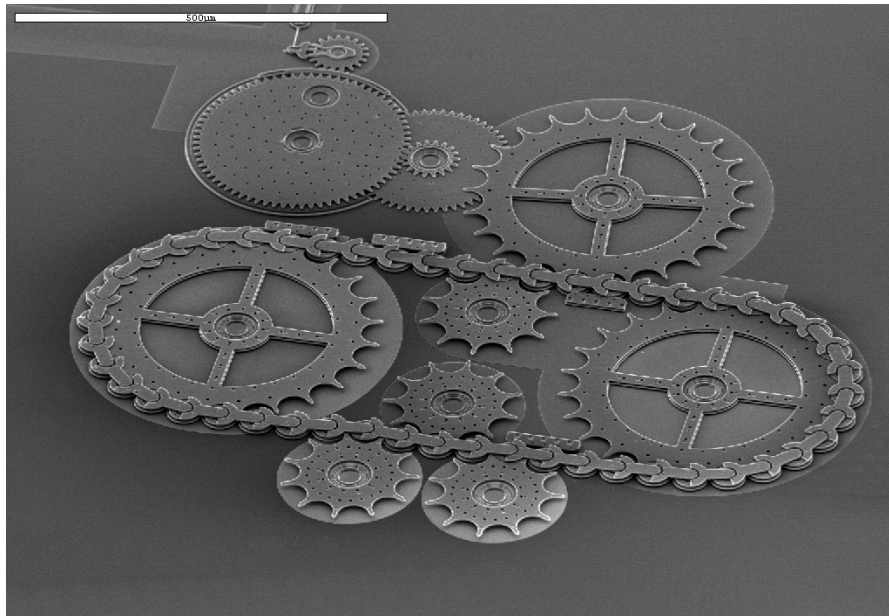
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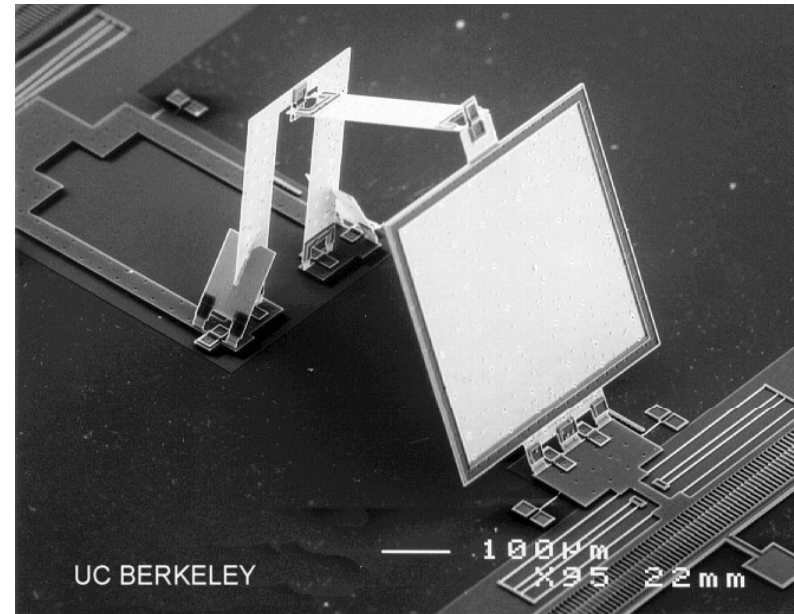
# Surface Micromachining ('85-'95)

- Micro gear chain  
(four polysilicon)



(Sandia Lab.)

- Actuated micromirrors  
(three polysilicon hinge structure)



(UC Berkeley, Pister Ph.D. thesis)



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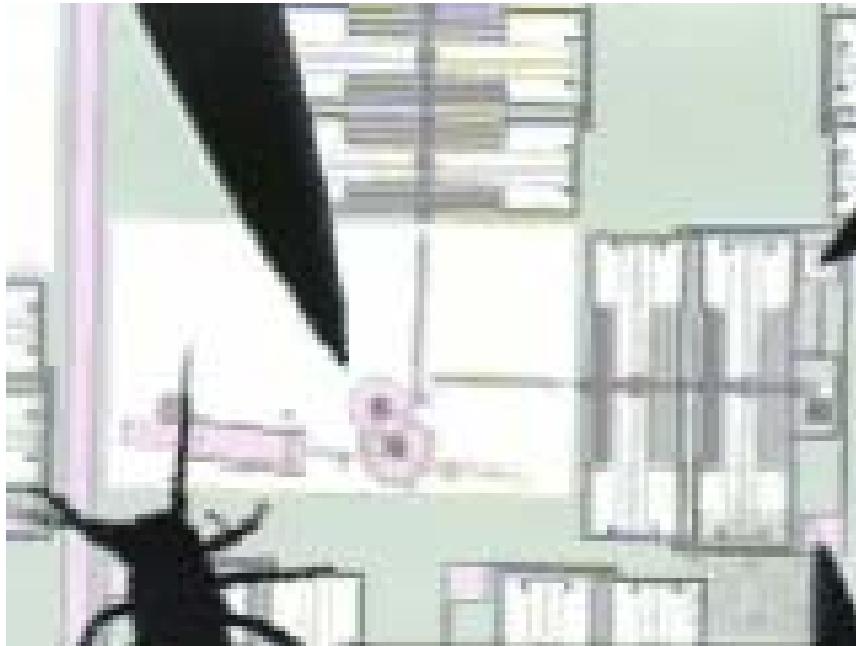
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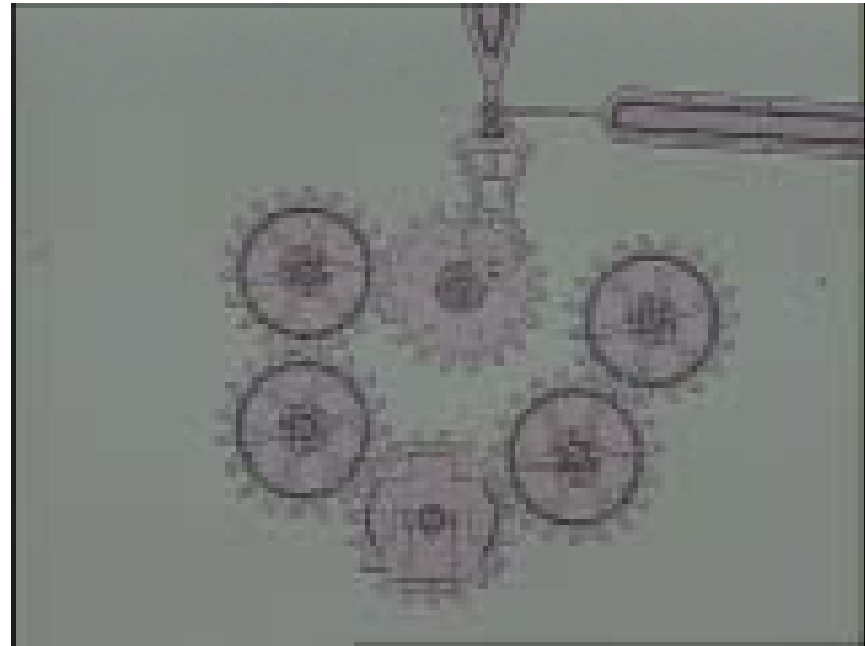
# Surface Micromachining ('85-'95)

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- Aphid on mirror



- 6 gears



(Sandia Lab.)



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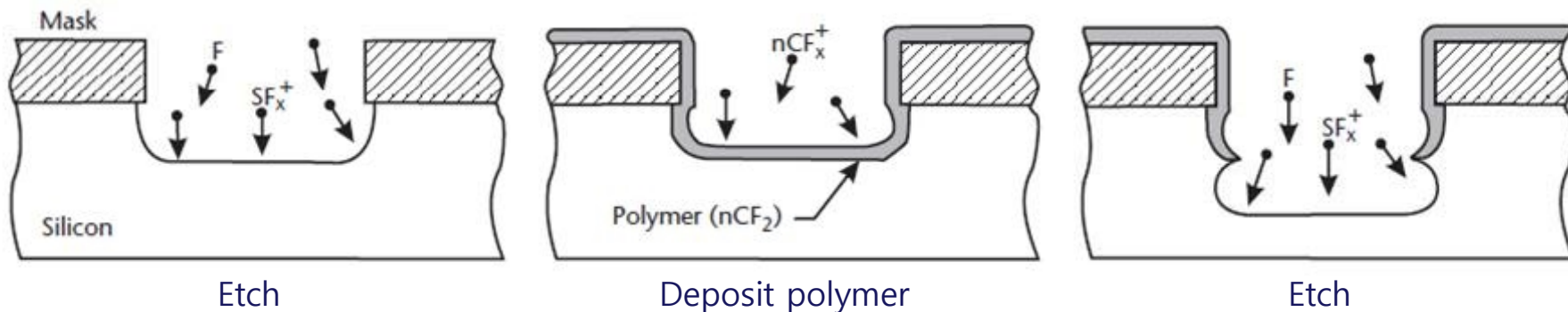
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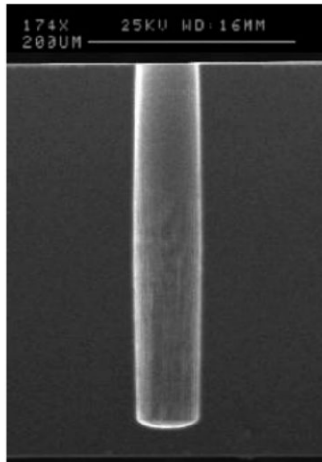
# Deep Silicon Reactive Ion Etching ('90- )

- Uses high density plasma to alternatively etch silicon and deposit etch resistant polymer on sidewall
  - Unconstrained geometry  $90^\circ$  side walls
  - High aspect ratio 1:30
  - Easily masked (PR,  $\text{SiO}_2$ )
- Bosch process: sidewall passivation  $\rightarrow$  etch  $\rightarrow$  sidewall passivation  $\rightarrow$  etch ...

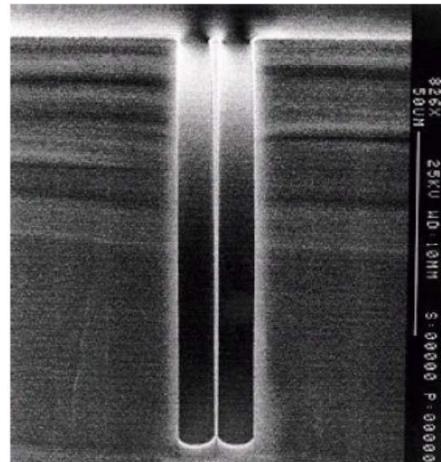


# Deep Silicon Reactive Ion Etching ('90- )

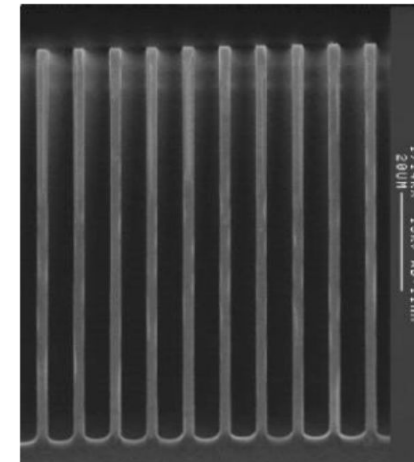
- Fabrication example



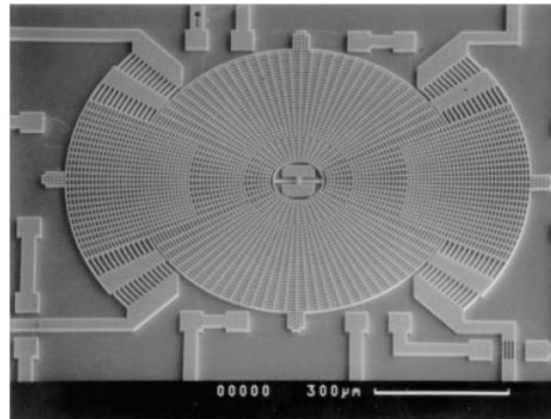
350  $\mu\text{m}$  depth



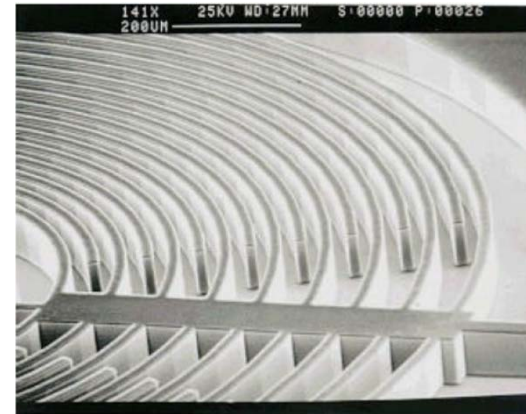
100  $\mu\text{m}$  depth



80  $\mu\text{m}$  depth, 4.5  $\mu\text{m}$  space width, 2  $\mu\text{m}$  line width



Gyroscope



Accelerometer (170  $\mu\text{m}$  depth)



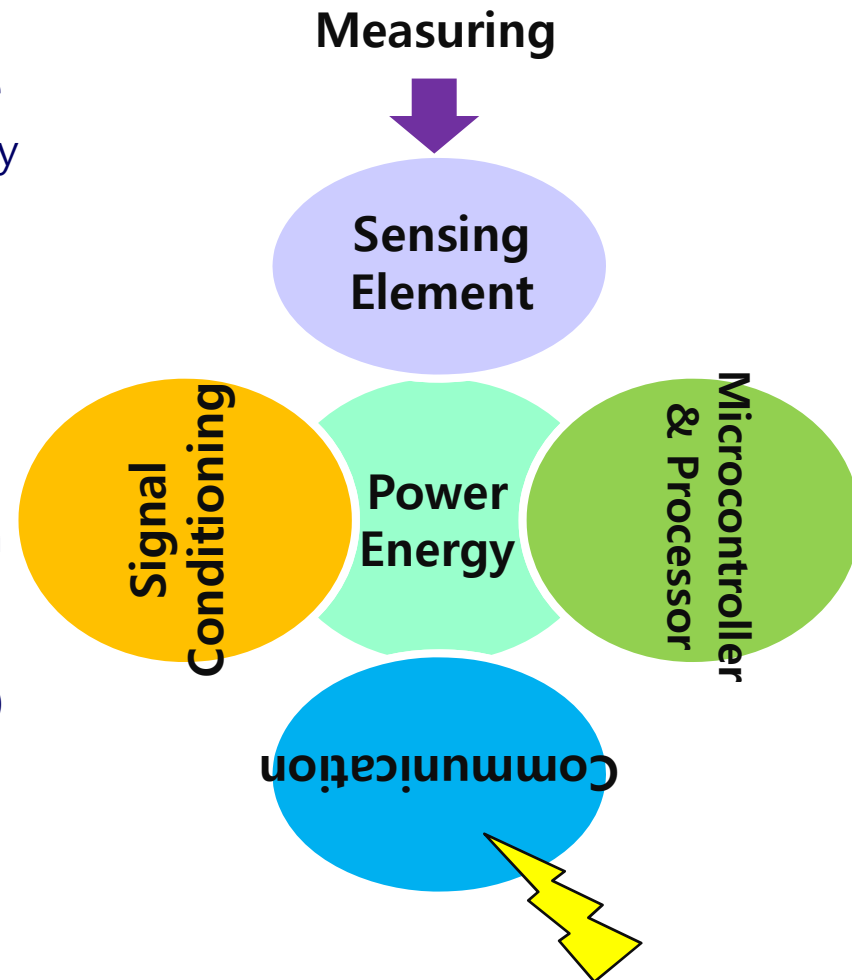
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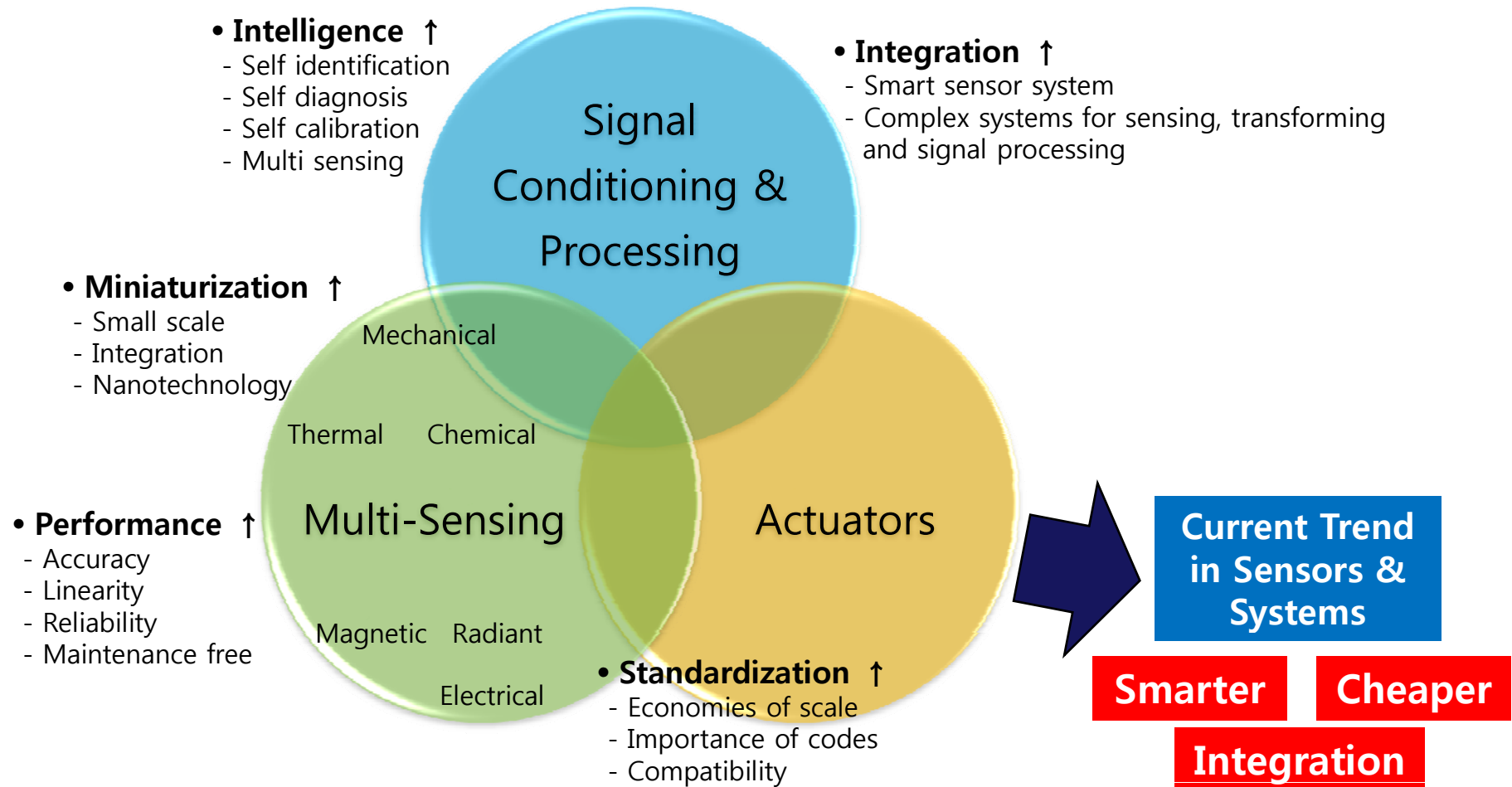
# Applications – Smart Sensors

- Smart sensor
  - A sensor with built-in intelligence
  - The intelligence is partially or fully integrated on a single chip
- Smart sensor architecture
  - Sensing element
  - Interface element for signal conditioning and data conversion
  - Processing element (this includes a microcontroller with an associated memory and software)
  - Communication element
  - Power source



# Applications – Smart Sensors (cont'd)

- Trend of the smart sensors



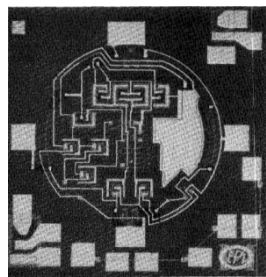
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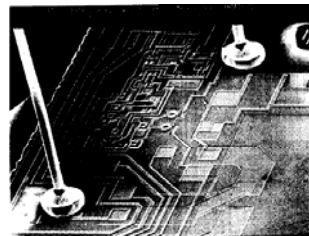
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# Applications – Smart Sensors (cont'd)

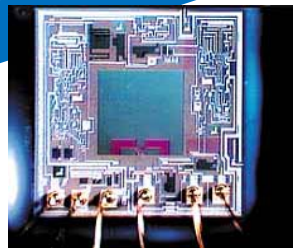
- Smart pressure sensors: piezoresistive or capacitive
  - Sensor + Electronics → Smaller & Cheaper
  - Key trends
    - The growth of the medical and automotive business is stable
    - New application like the TPMS are boosting this market



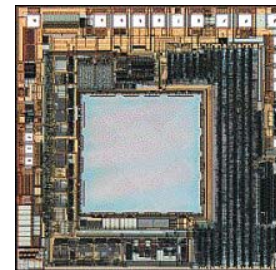
1980  
Uncompensated



1991  
Bipolar integrated



1985  
Temperature  
compensated



1999  
CMOS integrated  
(DSP)



2003  
Smart pressure sensor  
(TPMS)

2010  
Battery less TPMS



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# Applications – Smart Sensors (cont'd)

- Smart pressure sensors application
  - Engine optimization, emission control, and safety enhancement
    - Manifold intake air pressure (MAP) and barometric air pressure (BAP) for the engine control unit
    - Tire pressure monitoring system (TPMS) and side airbag pressure sensor
  - Medical applications
    - Sleep apnea, asthma monitoring, blood pressure meter



MAP sensor  
(Delphi)



Airbag pressure sensor  
(Bosch)



Wheel mounted TPMS  
(Siemens)



Blood pressure meter  
(Motorola)



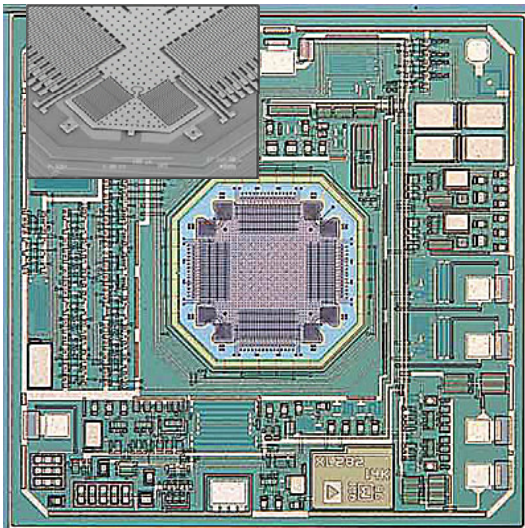
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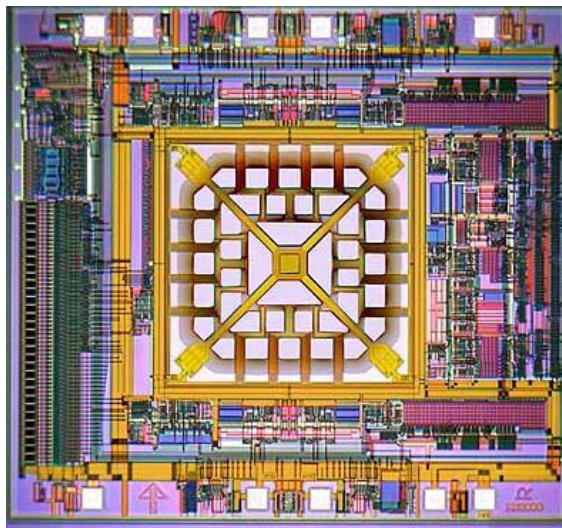
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# Applications – Smart Sensors (cont'd)

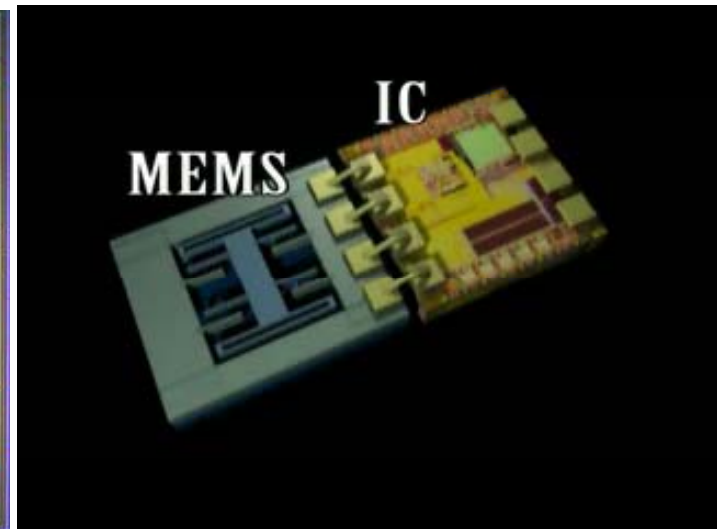
- Smart accelerometer: capacitive or thermal
  - Smaller devices with multiple axis sensing
  - Key trends
    - The automotive business is increasing rapidly with the growth of ESP
    - Consumer applications have really started use MEMS sensors in volume for application like mobile phone, GPS, and game controller



Capacitive accelerometer  
(ADI)



Dual-axis thermal accelerator  
(MEMSIC)



MEMS accelerometer with IC  
(NML SNU)



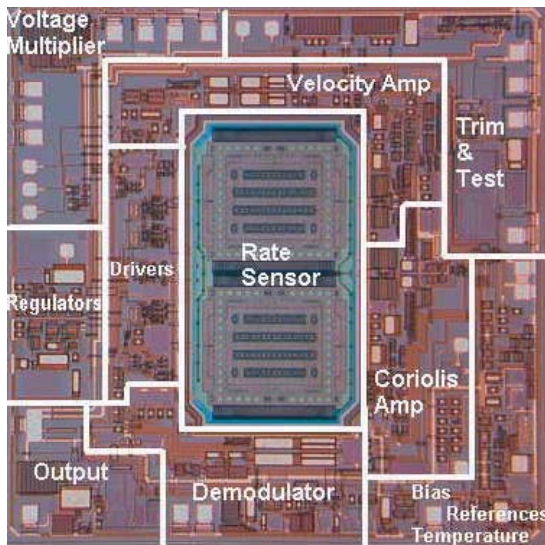
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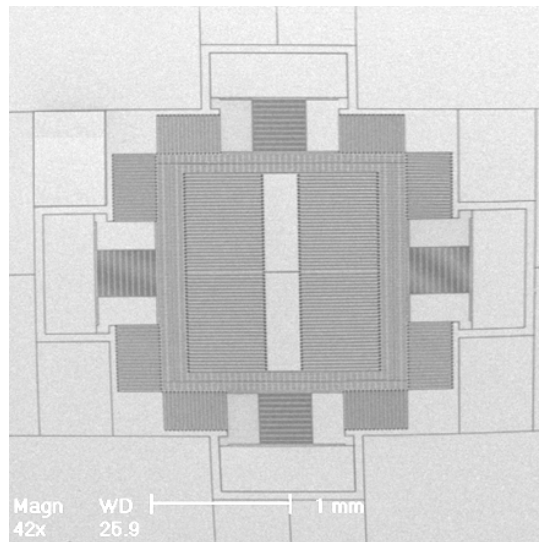
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# Applications – Smart Sensors (cont'd)

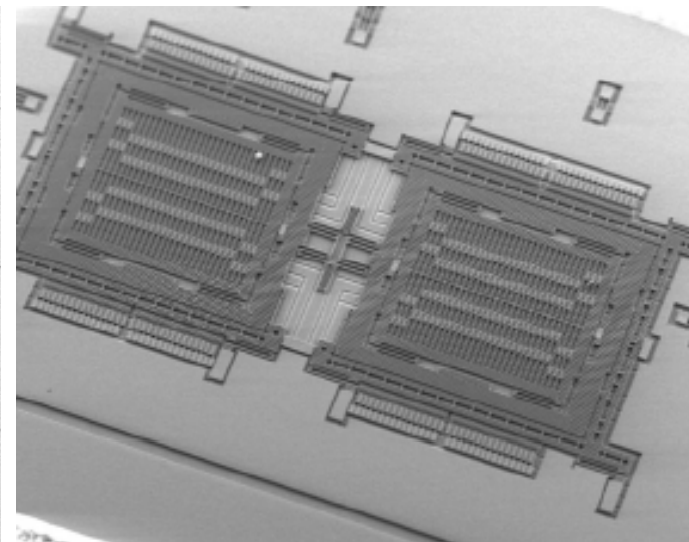
- Smart gyroscope : capacitive or piezoelectric
  - Smaller devices with multiple axis sensing
  - Key trends
    - The ESP market is growing very fast, with adoption of the system in medium end cars. (Silicon vs. Quartz)
    - GPS is another growth area, both for automotive and autonomous systems



iMEMS ADXRS  
(ADI)



X-axis gyroscope  
(SNU, NML)



Z-axis gyroscope  
(Motorola)



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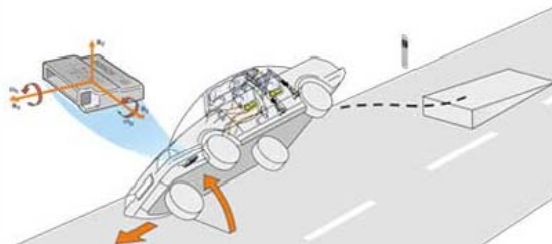
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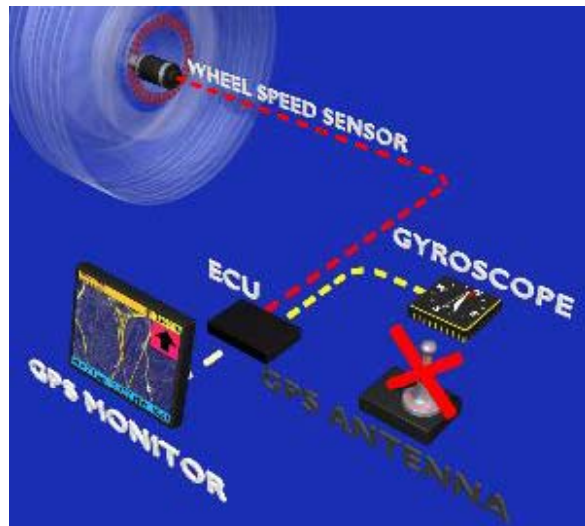


# Applications – Smart Sensors (cont'd)

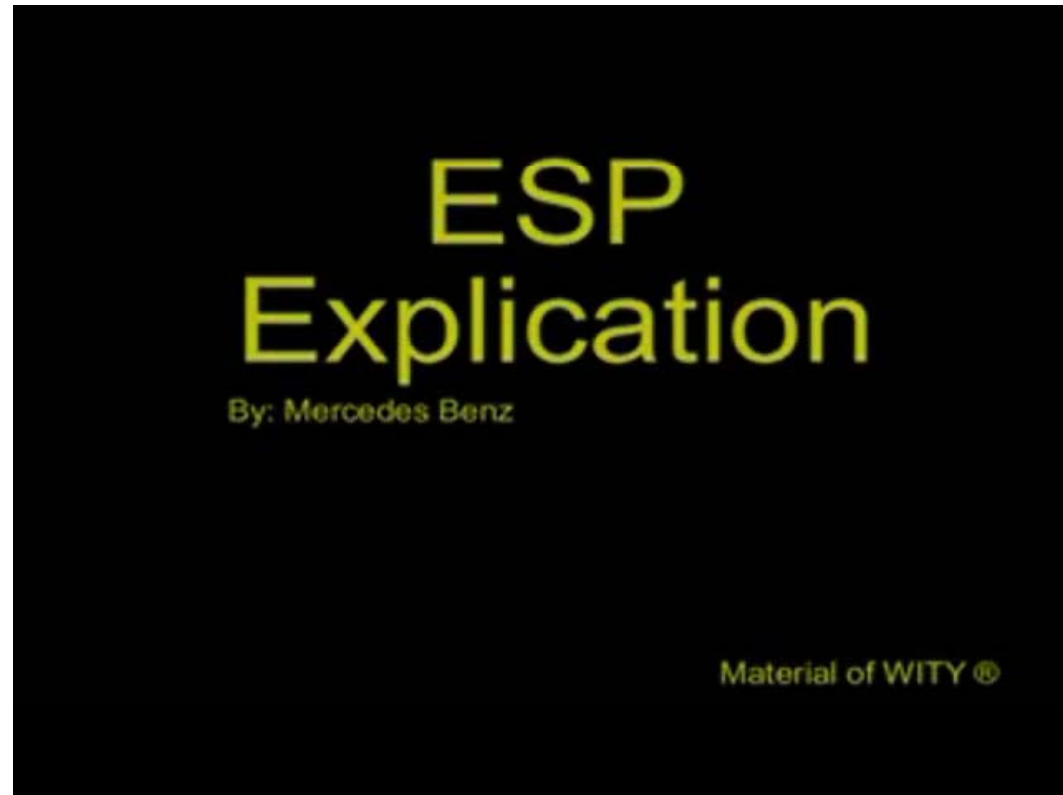
- Smart accelerometer & gyroscope for automotive applications
  - Crash accident recording, Rollover sensing, ESP, GPS



Rollover sensing



High performance GPS navigation with gyroscope



Electronic Stability Programs/Vehicle Dynamic Control (ESP/VDC)



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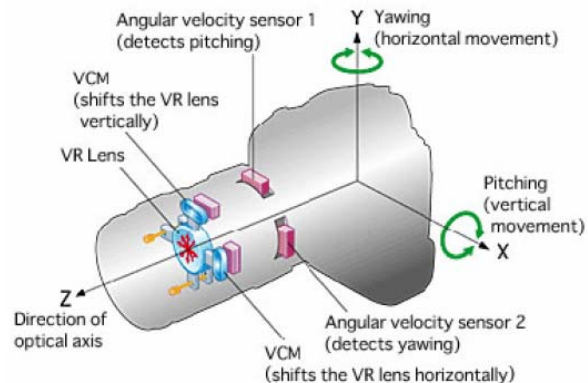
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# Applications – Smart Sensors (cont'd)

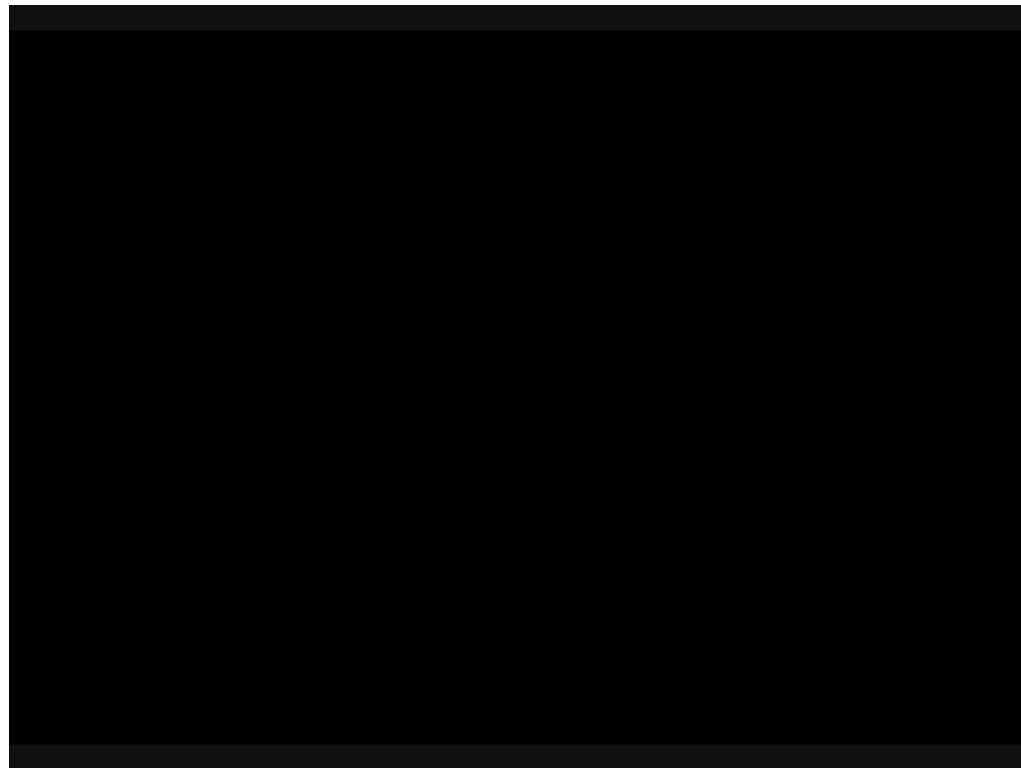
- Smart accelerometer & gyroscope for consumer electronics
  - Video game controller, camera image stabilization, HDD protection, mobile phone, human computer interface



Video game controller (Nintendo)



Lens shifting type (Nikon)



iPhone (Apple)



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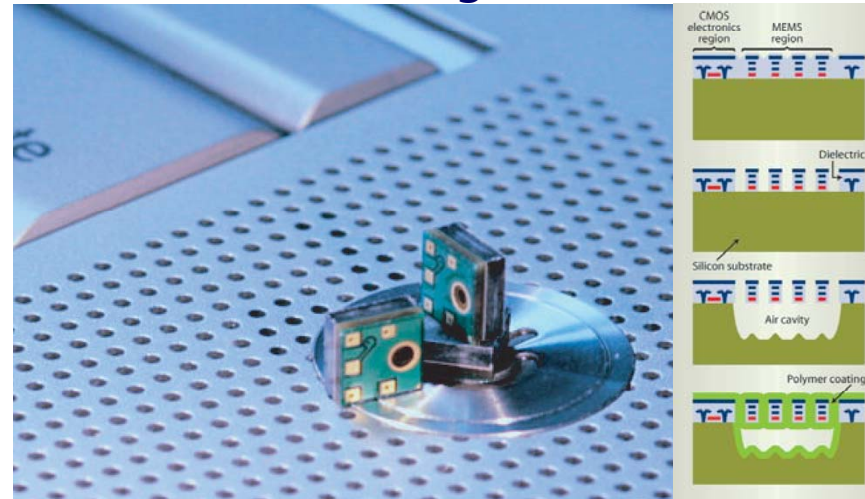
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# Applications – Smart Sensors (cont'd)

- MEMS microphone
  - Since 2004, the industry has seen increasing sales of MEMS devices across multiple consumer applications, with MEMS microphones for cell phones leading the pack.
  - The market for overall MEMS microphones will be 432 million units in 2008, according to Yole report.
- MEMS microphone applications: mobile phone, PDA, digicam, camcorder, lab-top, automotive (hand-free calling)



Silicon microphone  
(Knowles Acoustics)



Surface mountable monolithic digital microphone &  
Fabrication process for MEMS microphone (Akustica)



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# Applications – Smart Sensors (cont'd)

- Smart biomedical sensors
  - Biomedical sensors with integrated circuitry
  - Implanted in the human body or wearable
  - Will improve people's health, comfort and safety
  - Typical future sensor node
- Example applications
  - Glucose level monitor
  - Transplant organ viability monitor
  - Blood monitor
  - Cancer detection/monitor
  - Health monitor
  - Retinal and cortical prosthesis

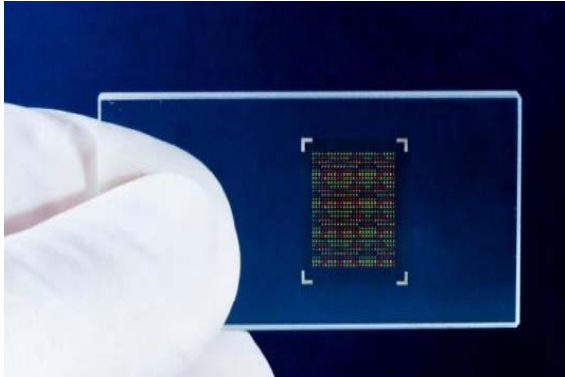


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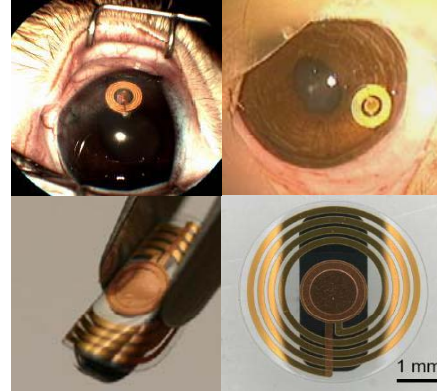
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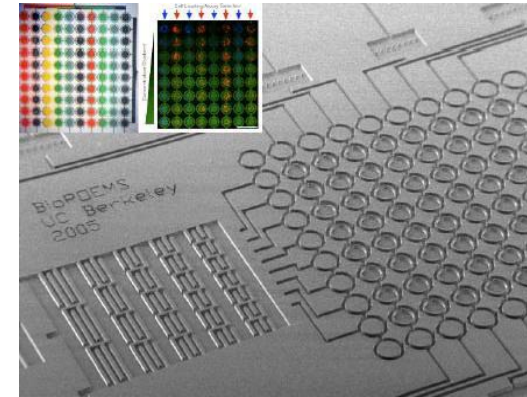
# Applications – Fluidics and BioMEMS



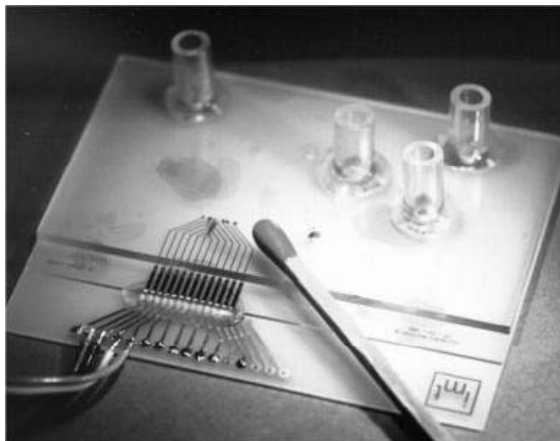
DNA chip (TorreyPath)



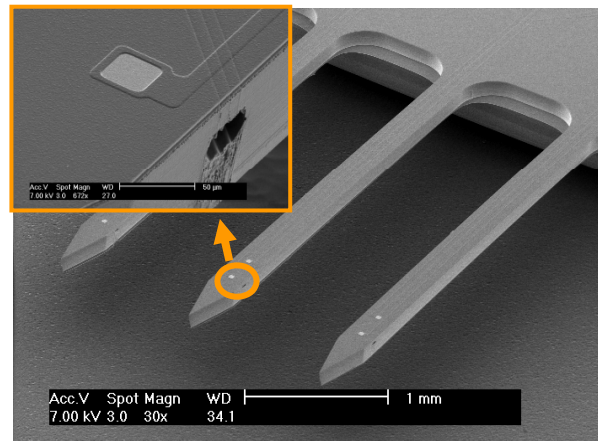
Pressure sensor (Caltech)



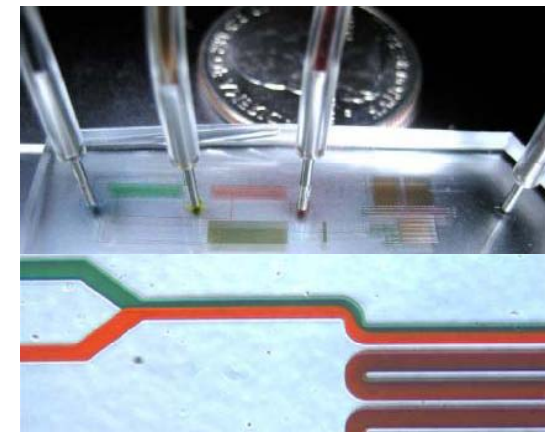
Dynamic cell culture array  
(U.C. Berkeley)



Nanopump (De GENEVE Univ.)



Microneedle (NML SNU)



Microfluidic system  
(U.C. Berkeley)



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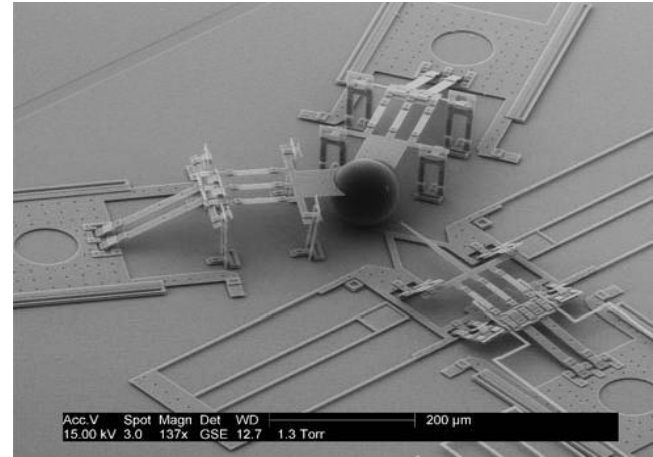
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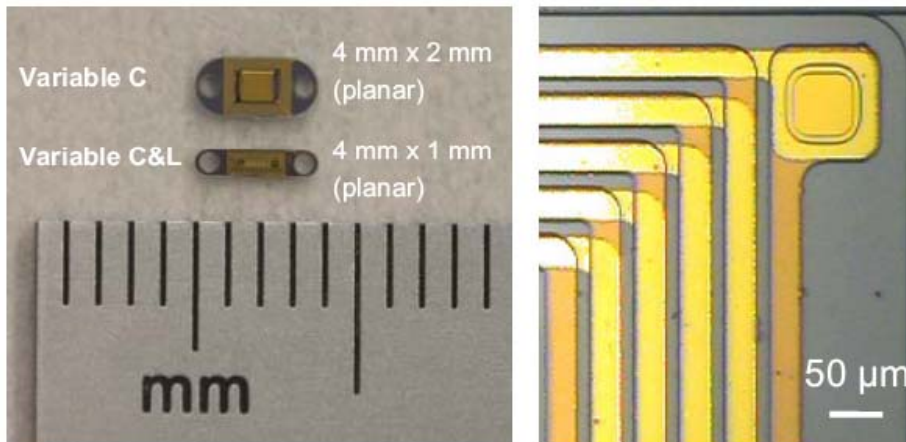
# Applications – Fluidics and BioMEMS (cont'd)



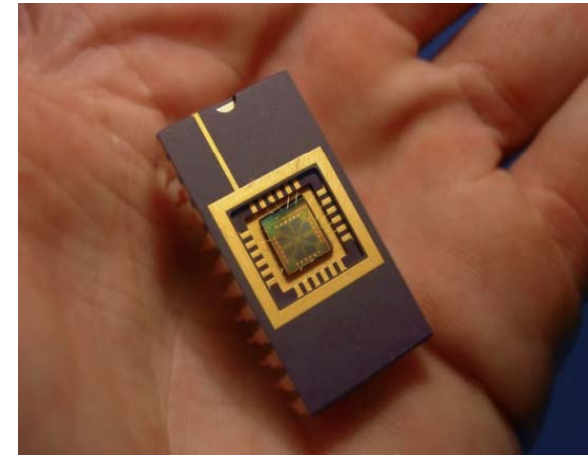
DNA chip (Roche)



Bio-MEMS Gripper(BYU)



Wireless intraocular pressure sensor (Doheny Eye Institute)



Biosensor (IMEC )



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# Applications – Fluidics and BioMEMS (cont'd)



- Neural Chip - The New Bionic Man
  - Retina Implant
  - Cochlear Implant
  - Edinburgh Arm
  - Heart Assist Pump
  - Nose on a chip
  - Electronic Tongue
  - NCP (NeuroCybernetic Prosthesis)  
: relief for the epileptic seizures,  
VNS (Vagus Nerve Stimulation)
  - Plastic muscle
  - Silicon Sensor

(Science, 8 February, 2002)



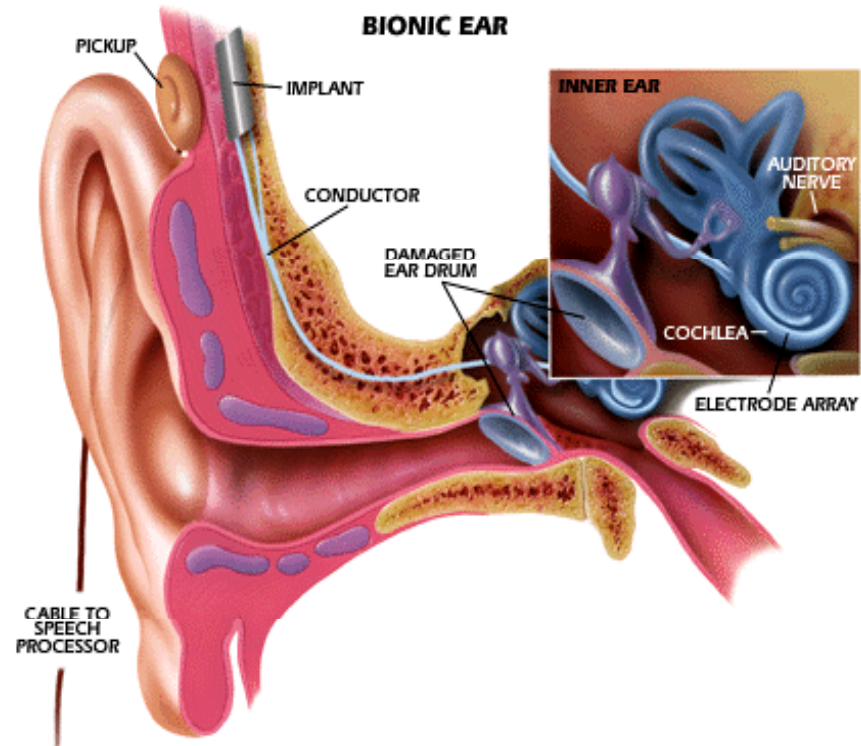
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# Applications – Fluidics and BioMEMS (cont'd)

- Cochlea prosthesis



Cochlear Inc.



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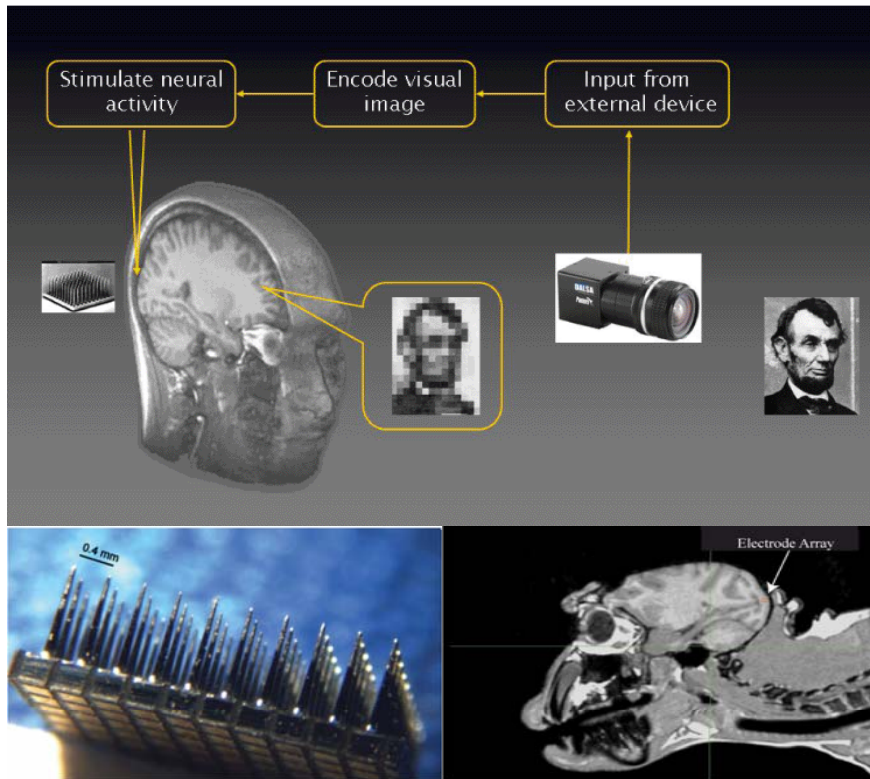
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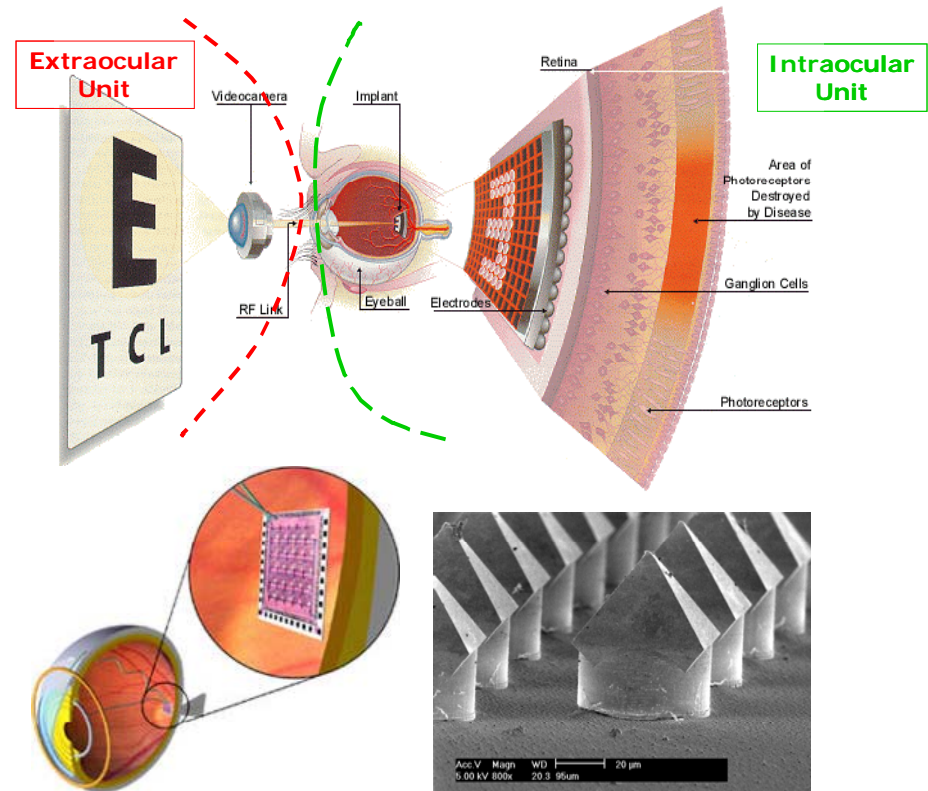


# Applications – Fluidics and BioMEMS (cont'd)

- Vision prosthesis



(The Univ. of Utah)



(Arrow-head Micro Electro Array, SNU)



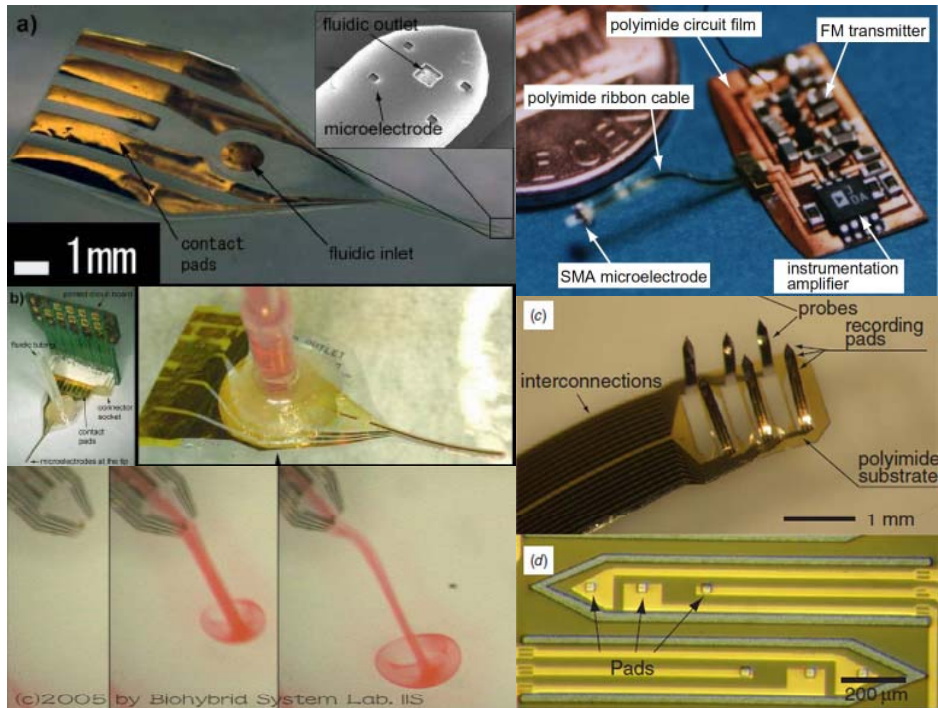
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# Applications – Fluidics and BioMEMS (cont'd)

- MEMS Neural probe



(The Univ. of Tokyo)



(Caltech)



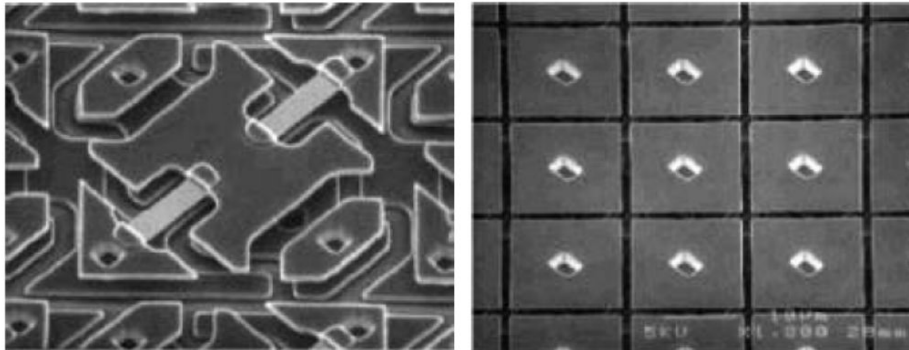
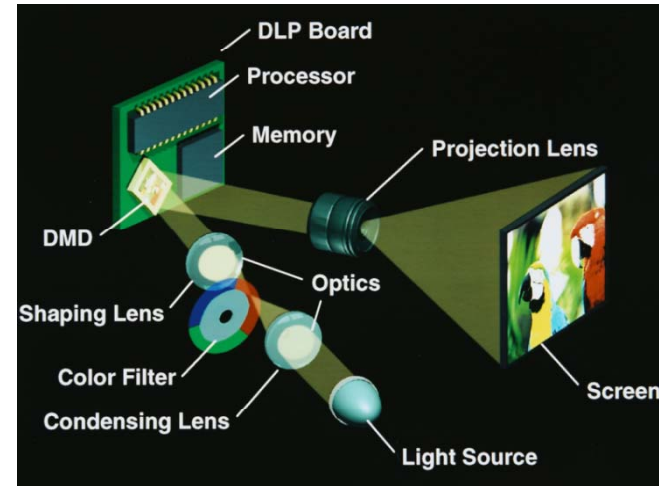
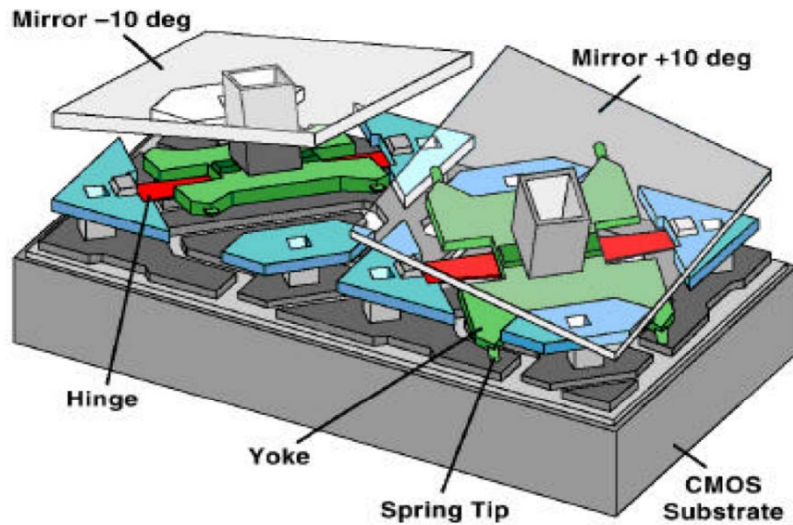
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# Applications – OMEMS (cont'd)

- DLP(digital light processing)



DLP Pico Projector Phone

(<http://www.dlp.com>)

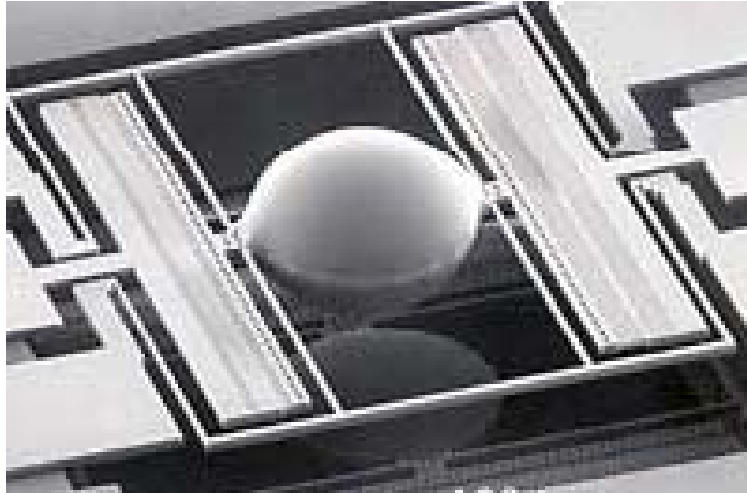


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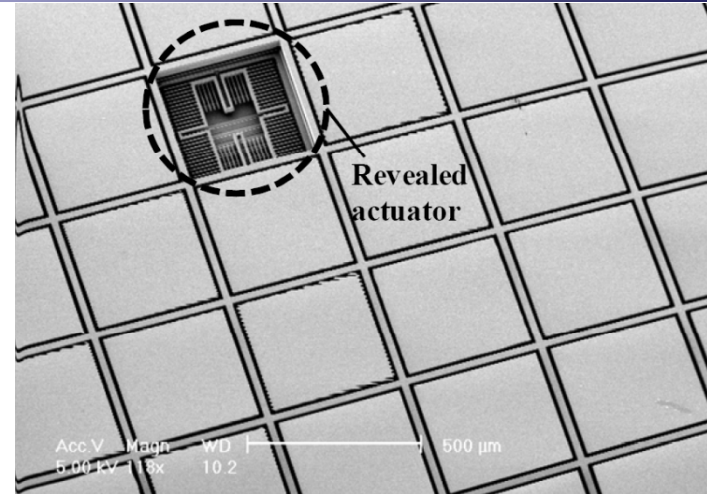
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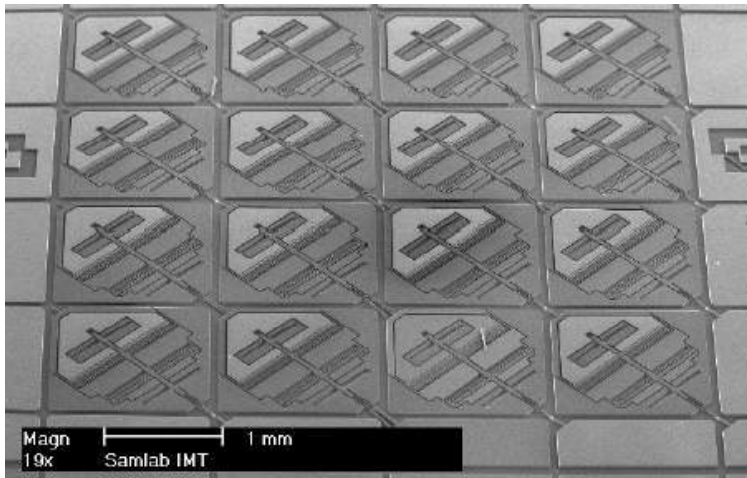
# Applications – OMEMS (cont'd)



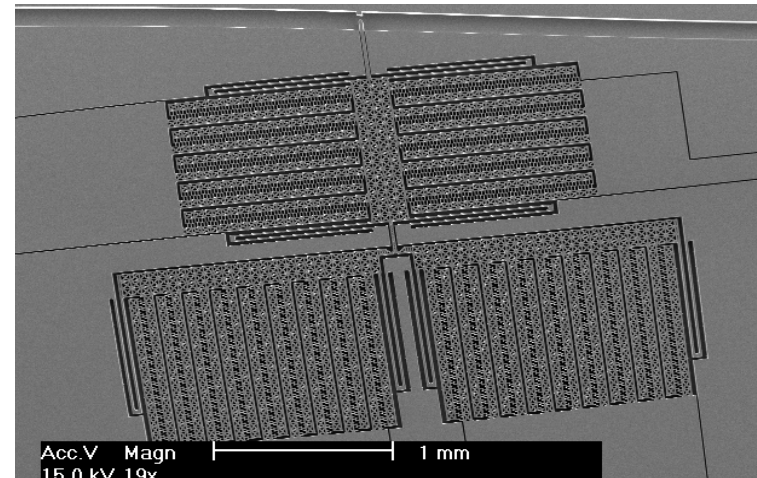
Micro-Lens Scanner (UC Berkeley)



Micromirror array for telescope (SNU)



4x4 matrix switch for optical fiber switching (Neuchatel Univ.)



Fast on/off optical switch (NML SNU)

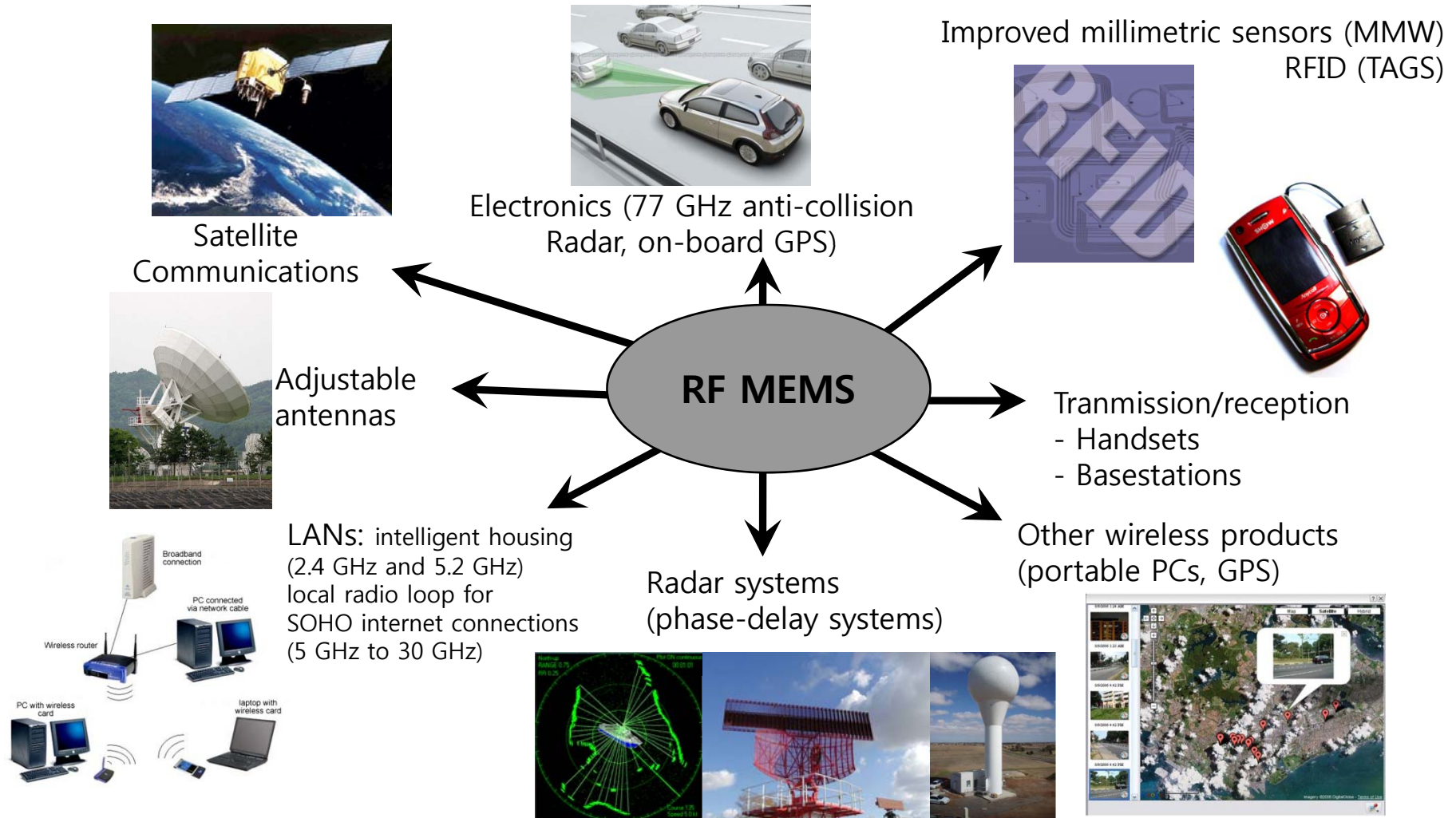


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# Applications – RF MEMS



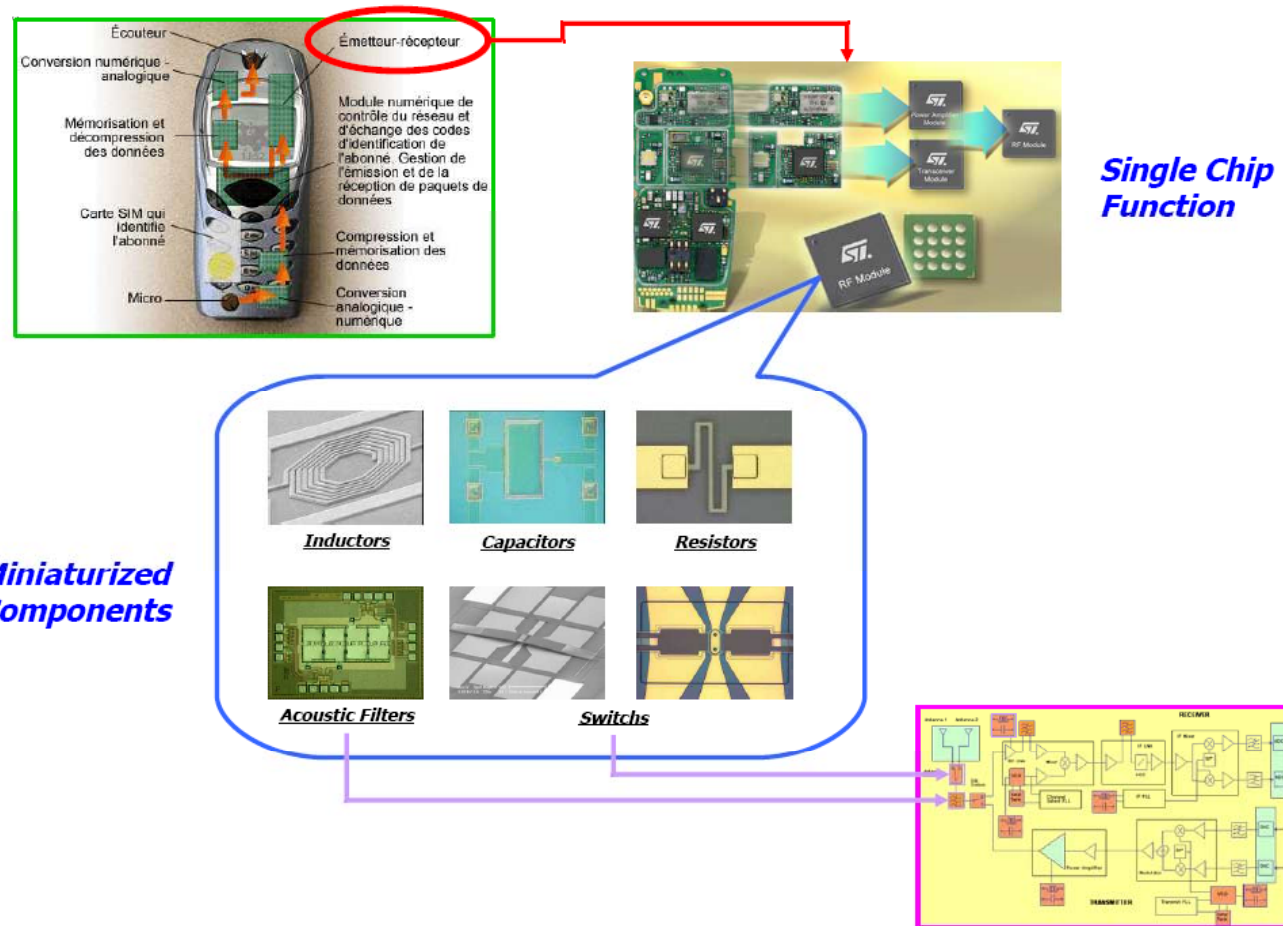
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# Applications – RF MEMS (cont'd)

- RF MEMS components for wireless devices



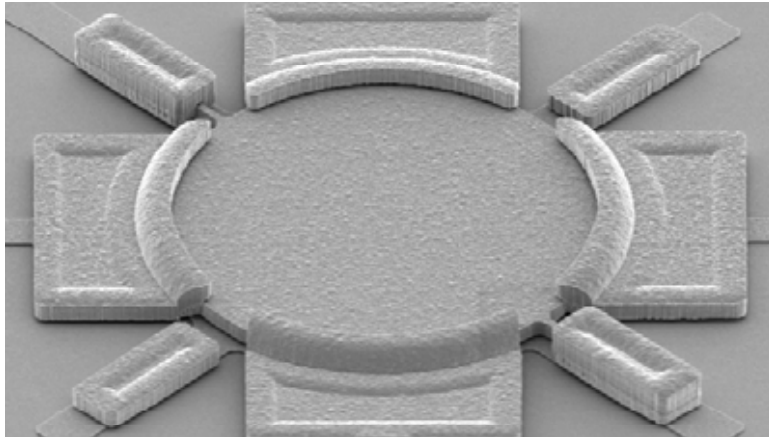
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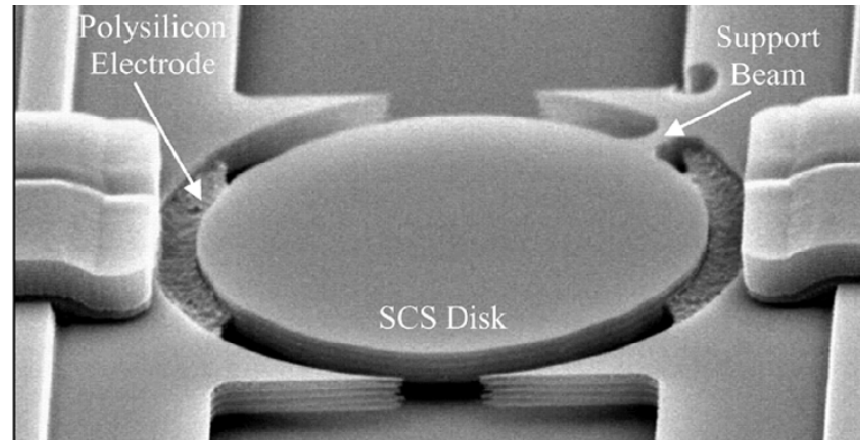
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# Applications – RF MEMS (cont'd)

- Vibrating RF MEMS devices

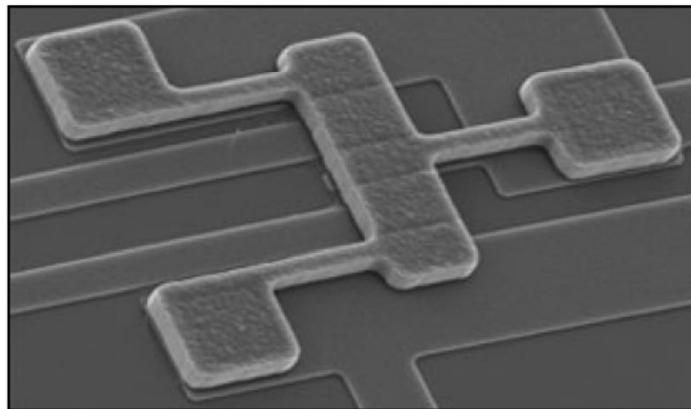


60-MHz wine-glass disk resonator (Michigan)



Side-supported SCS disk resonator (Georgia Tech.)

- Filters



Quadrature mixer-filter (Michigan)



Disk array composite μMechanical filter (Michigan)



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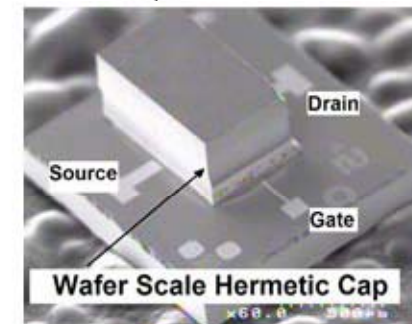
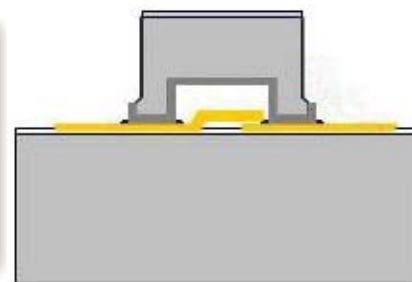
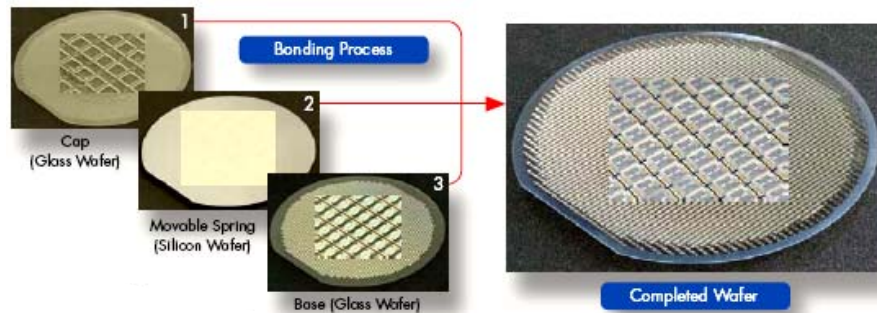
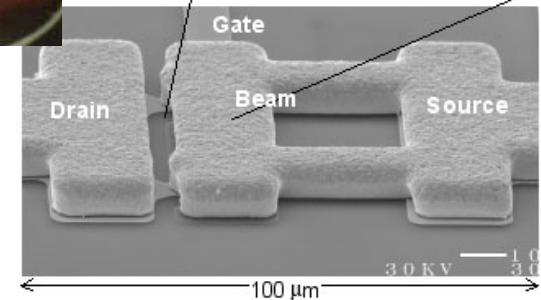
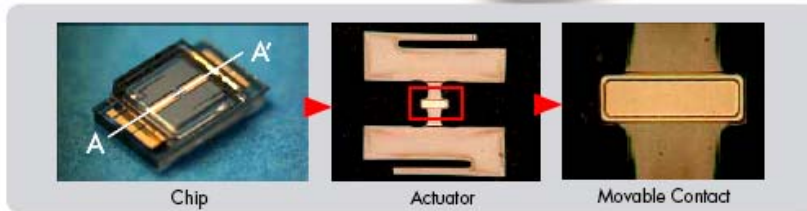
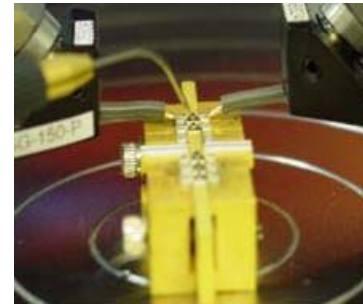
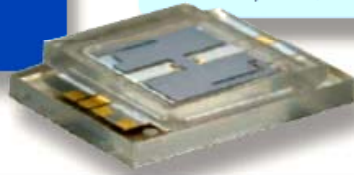
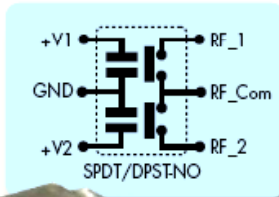
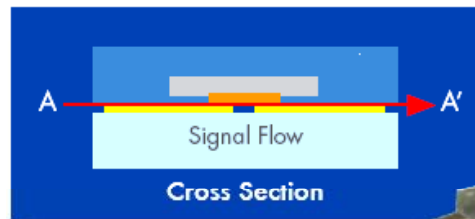
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# Applications – RF MEMS (cont'd)

- MEMS switch

RF-MEMS Switch Design



(Omron)

(RadantMEMS)



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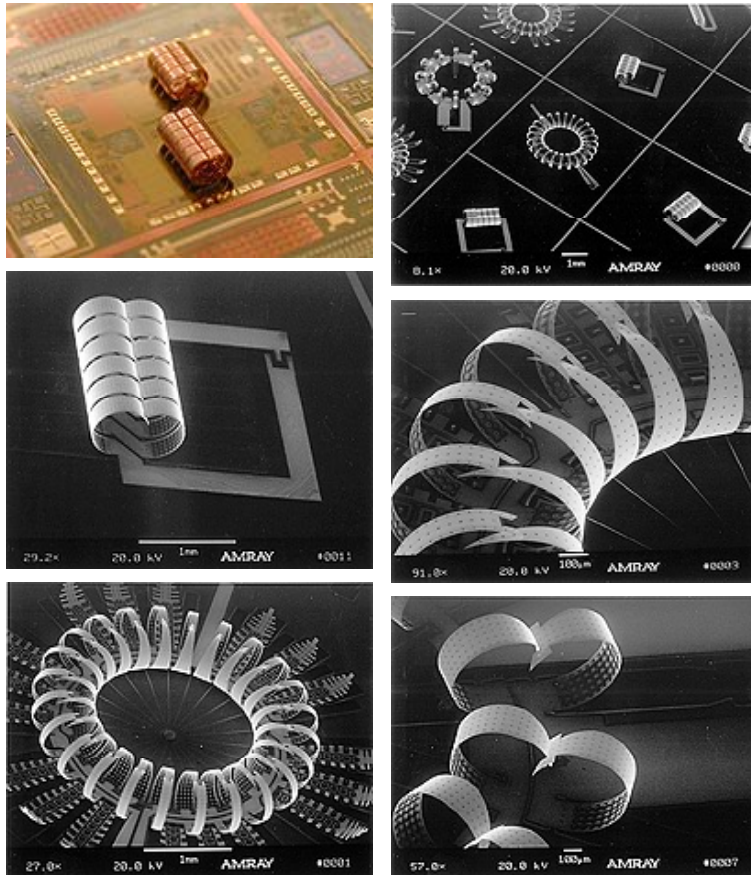
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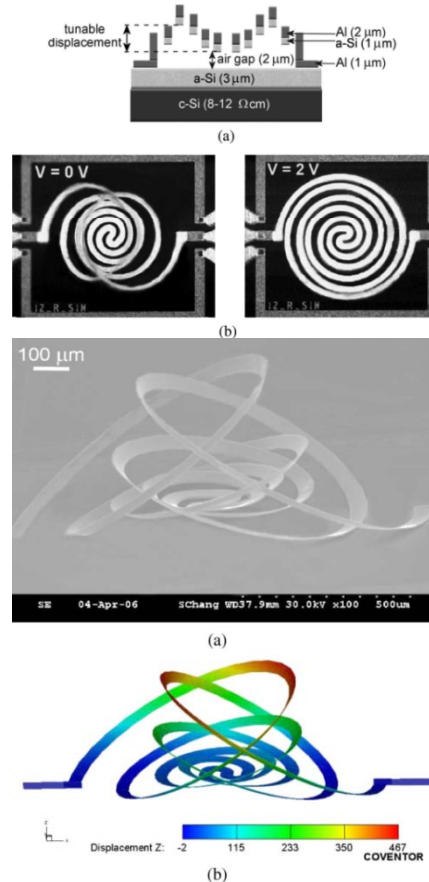


# Applications – RF MEMS (cont'd)

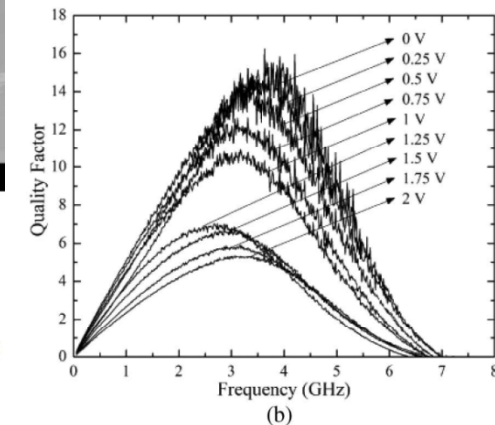
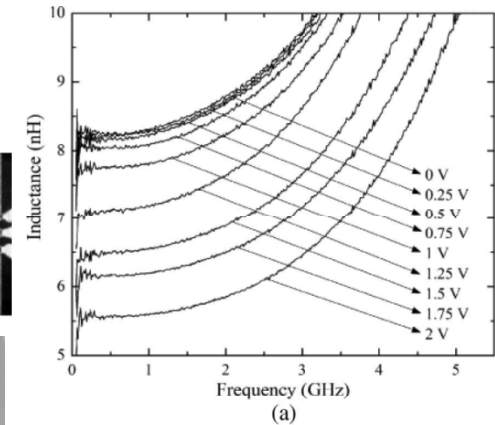
- MEMS inductor



Stressedmetal (PARC)



Tunable inductor (Univ. of Waterloo)



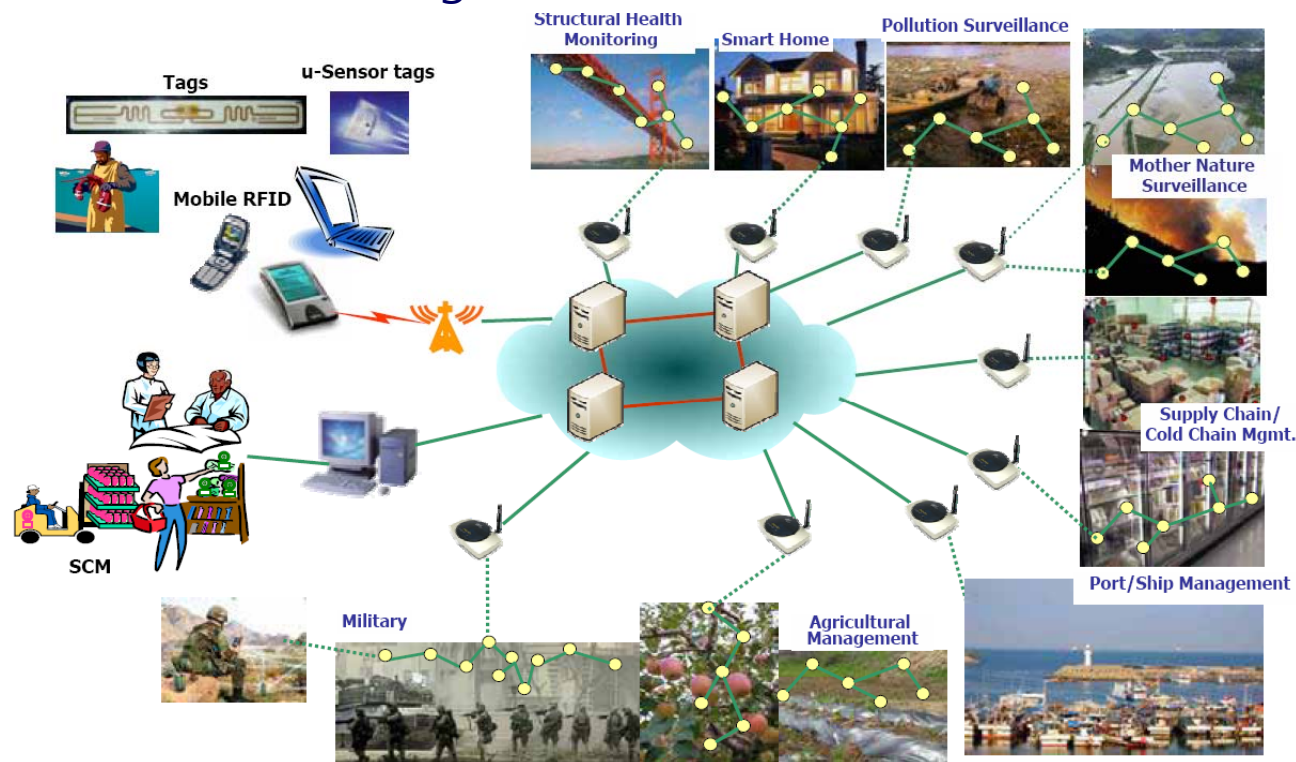
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# Applications – USN

- USN (Ubiquitous Sensor Network)
  - Everywhere, everything with RFID tags → Ubiquitous
  - Sensing ID and environmental information → Sensor
  - Real-time monitoring & control via network → Network



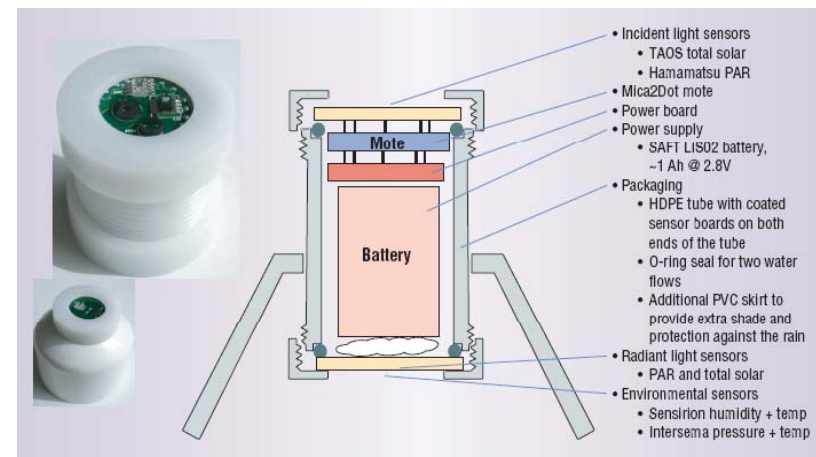
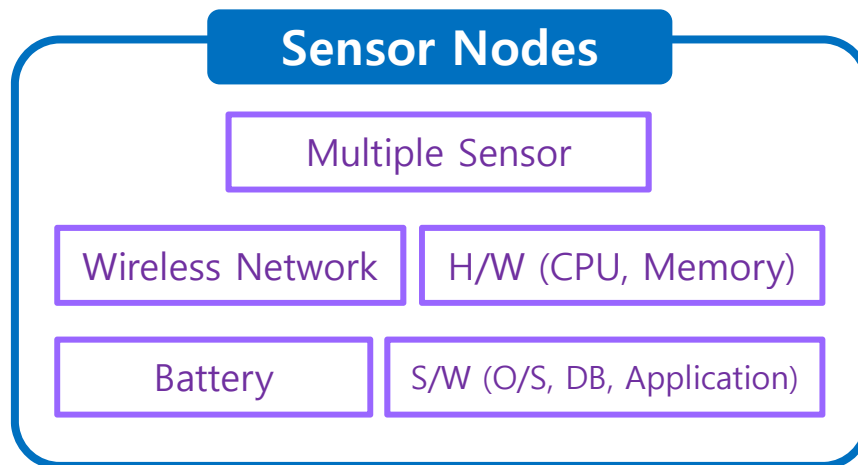
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# Applications – USN (cont'd)

- Sensor network and sensor nodes
  - Sensor network is composed of a large number of sensor nodes with sensing, processing & wireless communication capabilities
  - Sensor nodes are small, low cost, low-power devices that have following functionality:
    - Communication on short distances due to power limitation
    - Sense environment data
    - Perform limited data processing
  - Network usually also contains “sink” node which connects it to the outside world



Self-organizing wireless sensor network nodes: Mote (Intel)



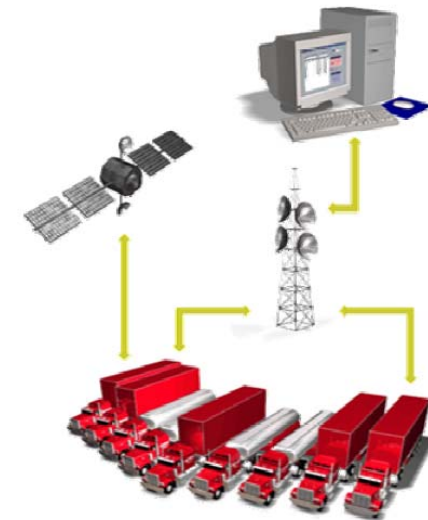
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# Applications – USN (cont'd)

- Sensor Network Applications
  - Military Applications
  - Environment and Habitat Monitoring
  - Manufacturing
  - Transportation
  - Seismic Study
  - Health Care
  - Home Network



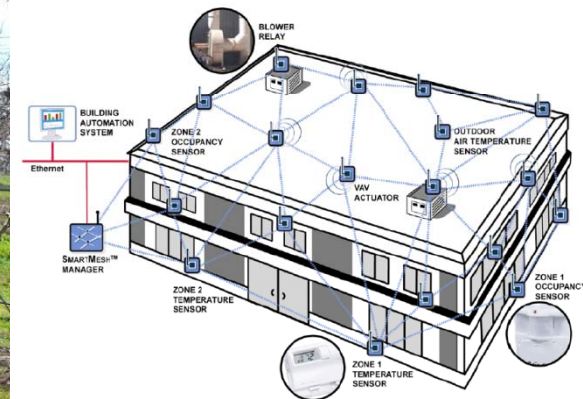
Transportation



Military applications



Soil moisture sensor nodes



Building automation system



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